

Selected Novel Technologies for Licensing

2012
MRS
Fall

Innovative Materials
for your Products

Devices

Advanced Materials

Oxide

Carbon

Metal

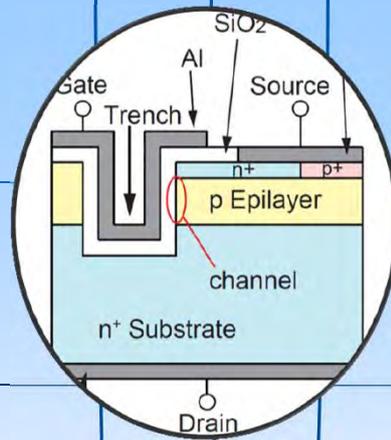
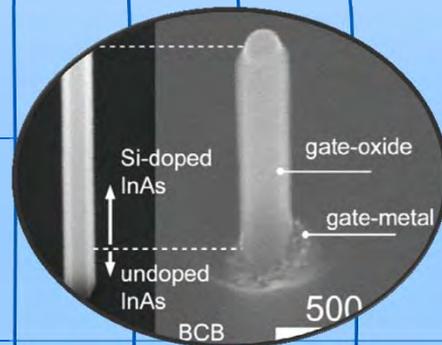
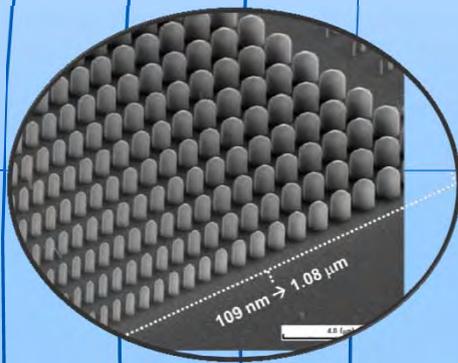
Soft Material

Measuring Equipment



Japan Science and Technology Agency

Devices

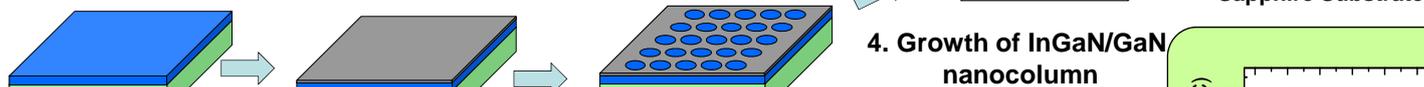


Growth of InGaN/GaN Nanocolumn Arrays and their LEDs

Prof. Katsumi KISHINO & Associate Prof. Akihiko KIKUCHI (Sophia University)

1. Growth of InGaN/GaN Nanocolumn Arrays

- We found a regularly arranged InGaN/GaN nanocolumn array is fabricated using Ti-mask selective-area growth (i.e. Ti-nano-hole-patterned GaN templates on sapphire substrate) by RF-plasma-assisted MBE.



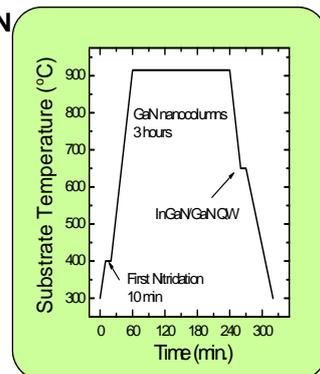
1. MOVPE-GaN template (3.5μm)

2. Ti thin film deposition

3. make Ti nano-hole by FIB technique

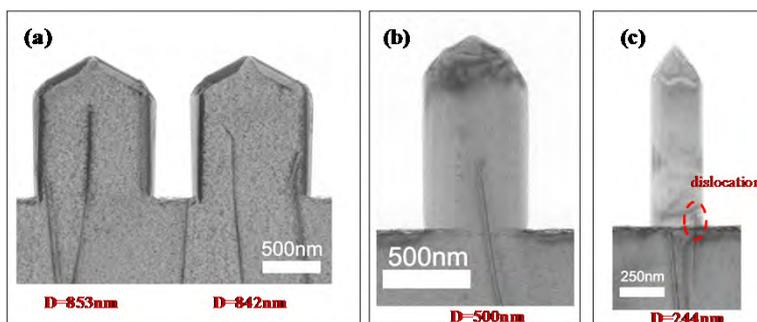
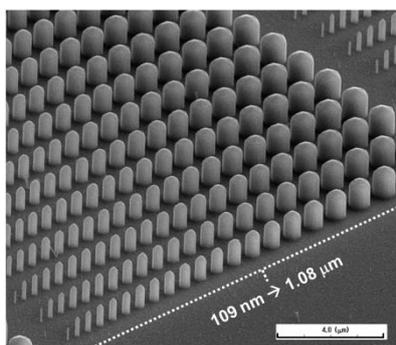
Period: 400, 600 nm
Hole size: ~150 nm

4. Growth of InGaN/GaN nanocolumn

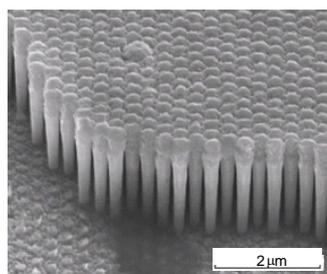
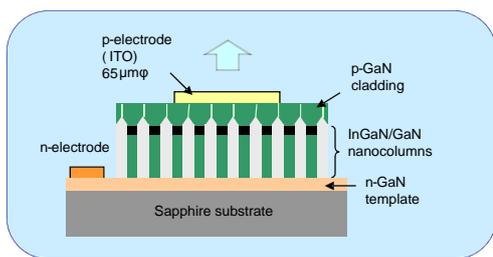


2. Crystallinity Control by Nanocolumn Diameter

- Fabrication Control of Nanocolumn Diameter
- Dislocation density is minimized in nanocolumn of less than 250nm diameter

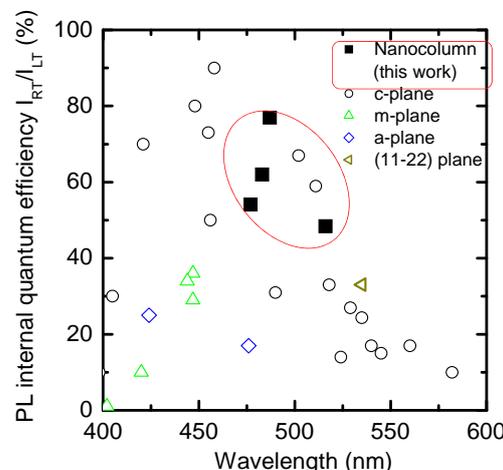
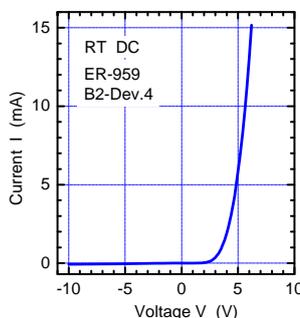


3. Fabrication of Nanocolumn LED



ITO electrode
p-type GaN cladding
p-type AlGaIn EBL (10nm thick)
InGaN(3nm)/GaIn(12nm) MQW (3-period)
InGaN(1.5nm)/GaIn(1.5nm) superlattice (25-period)

- Green LED of nanocolumn InGaN/GaN arrays shows a higher PL efficiency which means good crystallinity of the arrays.



4. Patent available for licensing

Patent No. : WO/2009/031276, WO2009/069286, WO/2010/023921 (JP,US,EP,KR,CN,TW)

Contact : Masaru OZAKI (JST)
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PL efficiencies as a function of peak wavelength

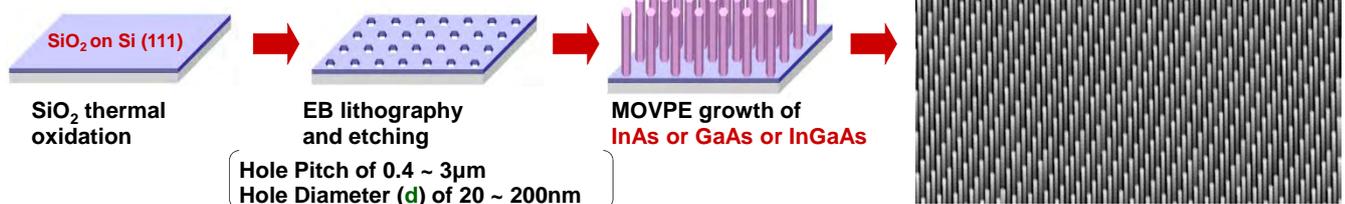
Steep-Slope Tunnel Field-Effect Transistor (FET) using III-V Nanowire on Si

Prof. Takashi FUKUI & Dr. Katsuhiro TOMIOKA (Hokkaido University)

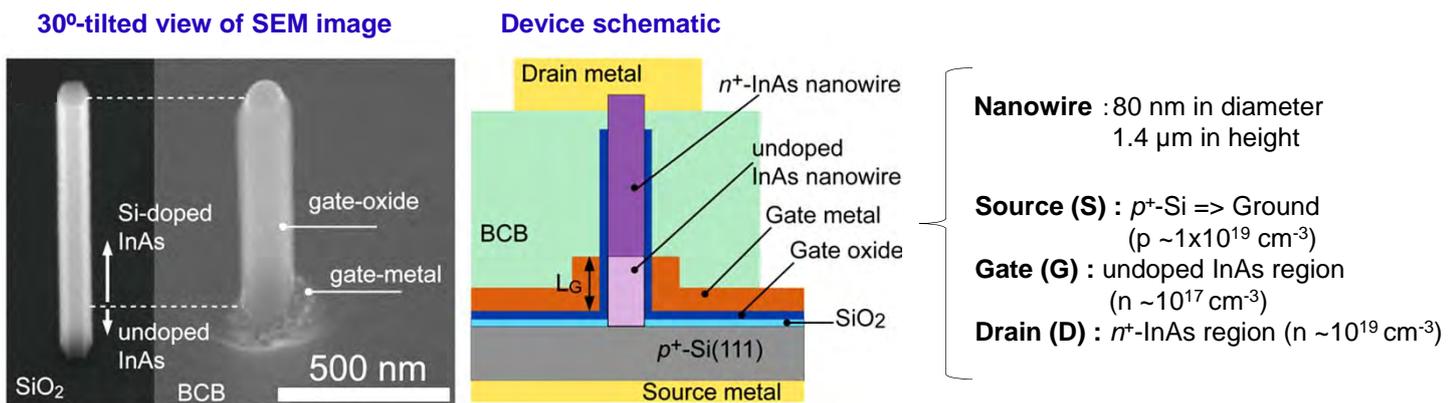
- As the scaling of Si transistors is reaching its limit, they are expected to have new gate architectures, channel materials and switching mechanisms which have both high integration and low power consumption.
- Our tunnel FET is a next generation transistor exceeding the limit of Si transistors.

1. Epitaxial Growth of III-V Nanowire on Si

- Tunnel FET has not been achieved because narrow band gap III-V/Si is a highly mismatched system.
- Selective area growth brings epitaxial III-V nanowire on Si (111) substrate

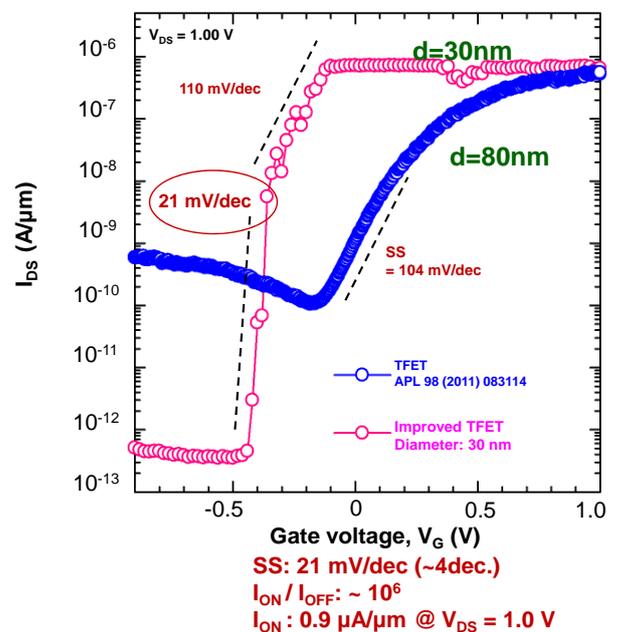
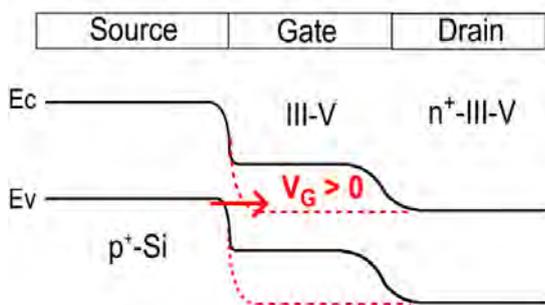


2. Device Structure of Vertical Tunnel FET



3. High Performance of Vertical Tunnel FET

- The combination of a narrow band gap III-V with Si is a good system for boosting up the ON-state current and has high band-to-band tunneling efficiency.
- Very steep turn-on switching was observed. The subthreshold slope (SS) is far lower value than 60mV/dec. (theoretical limit value) of Si FET.



4. Patent available for licensing

Patent No. : WO/2011/040012
(JP,US,EP,KR,CN)

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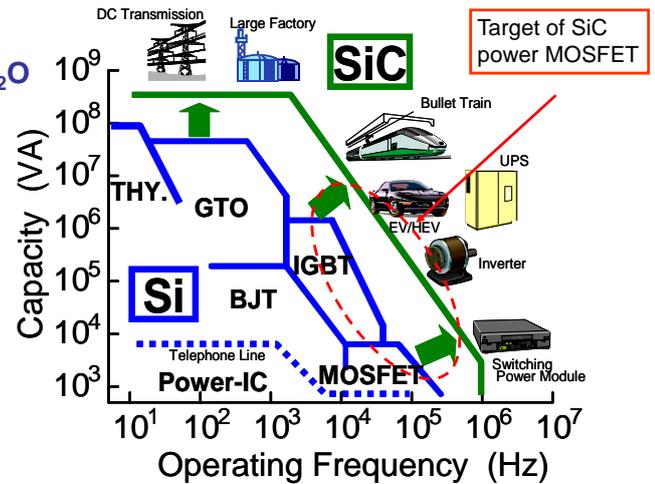
4H-SiC MOSFETs with High Channel Mobility by P-Doped Gate Oxide

Assistant Prof. Hiroshi YANO (NAIST)

1. 4H-SiC MOSFET

- Expected as ultra-low power loss devices
- Typical channel mobility obtained by nitridation, NO or N₂O annealing, was 20-40 cm²/Vs.
Low channel mobility is a big issue!
- We need to make efforts to find other techniques.

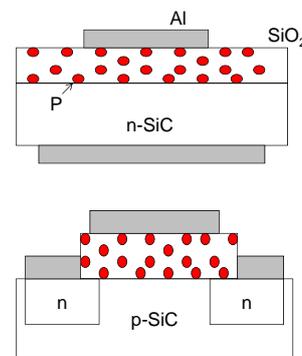
P-doped Gate oxide by POCl₃ annealing reduces D_{it} (< 1x10¹¹ cm⁻²eV⁻¹) and improves channel mobility (~ 100 cm²/Vsec).



2. Device Fabrication with P-Doped Gate SiO₂

(0001) Si-face 4H-SiC

- Dry oxidation (t_{ox} ~ 55 nm) ; 1200 °C, 160 min
- POCl₃ anneal ; 1000 °C, 10 min
- N₂ anneal ; 1000 °C, 30 min
- Al electrode evaporation
- N₂ PMA ; 400 °C, 30 min

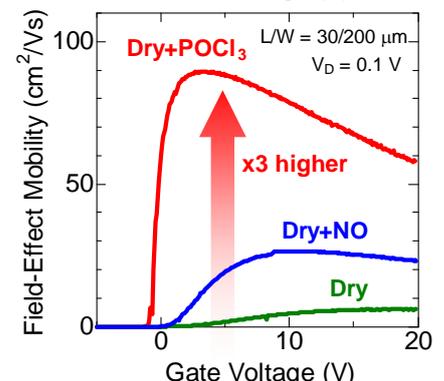
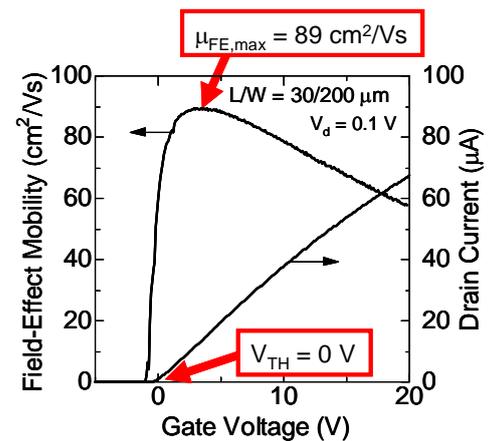
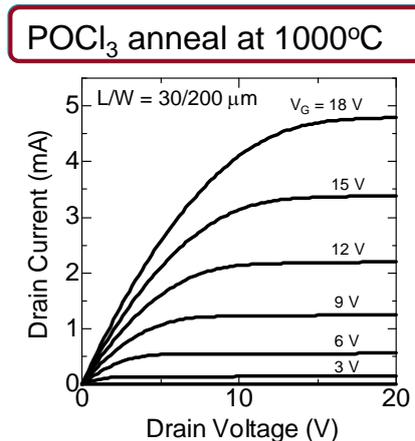
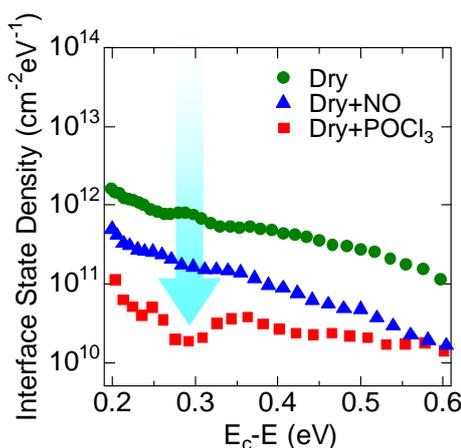


N-MOS Capacitor
(Gate diameter=300μm)

N-Channel MOSFET
(Channel length/Width = 30/200μm)

3. MOSFET Performance with P-doped Oxide Gate

- D_{it} can be reduced by POCl₃ anneal
- High field-effect mobility, μ_{FE,max} = 89 cm²/Vs



4. Patent available for licensing

Patent No. : WO/2011/074237
(JP,US,EP,KR,CN)

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4H-SiC Trench MOSFETs with High Channel Mobility by using Tilted Trench Sidewalls

Assistant Prof. Hiroshi YANO (NAIST)

1. Trench MOSFET

- Trench MOSFET is a favorable structure to achieve low on-resistance because of reasons below.
 - Channel on-trench sidewall
 - High channel density
 - No JFET (Junction Field Effect Transistor) region
 - Use of $\{11\bar{2}0\}$ face

Low on-resistance

Off-angle dependence was not clarified.

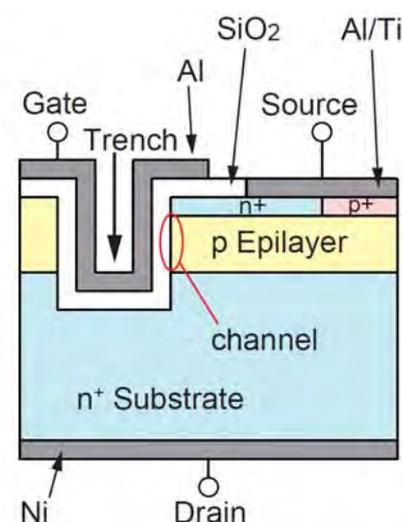
Electrical properties of trench MOSFETs on various off-angle substances have studied in this study.

$\{11\bar{2}0\}$ or $\{\bar{1}2\bar{1}0\}$ faces tilted by 15° toward $[000\bar{1}]$ bring SiC trench MOSFETs with high channel mobility ($\sim 100 \text{ cm}^2/\text{Vs}$).

2. Fabrication of Trench MOSFET

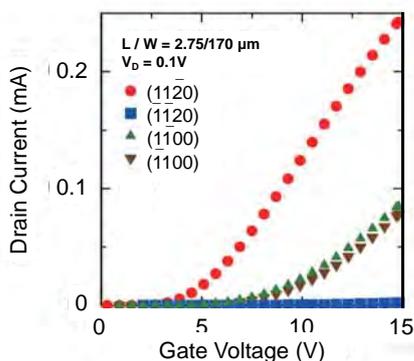
$4^\circ, 8^\circ, 15^\circ$ -off toward $[\bar{1}\bar{1}20]$ and 8° -off toward $[1\bar{1}00]$
C-face, 4H-SiC, n-Substrates (p-epi)

- Ion implantation (Al, P)
- Trench etching (ICP-RIE ($\text{SF}_6, \text{Ar}, \text{O}_2$))
- Thermal oxidation (in wet O_2 ($1100^\circ\text{C}, 1.5\text{h}$) + NO anneal ($1150^\circ\text{C}, 1\text{h}$))
- Formation of source (Al/Ti) and drain contacts (Ni)
- Metallization annealing (in $\text{N}_2 + \text{H}_2$ ($1000^\circ\text{C}, 2\text{min}$))
- Deposition of gate electrodes (Al)

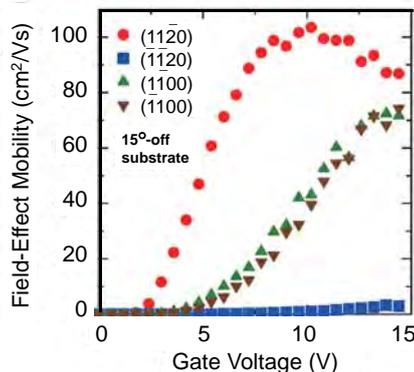


3. Channel Mobility in MOSFET Performance

- The substrate of 15° off-toward $[\bar{1}\bar{1}20]$ shows quite high drain current and high field-effect mobility.



I_d - V_g for each plane on 15 off-substrates



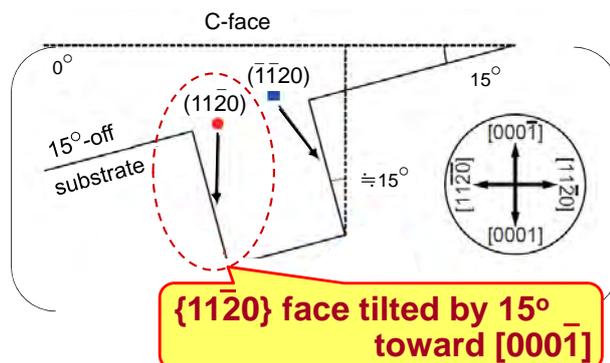
Off angle/Off direction	(1120)	($\bar{1}\bar{1}20$)	(1 $\bar{1}00$)	($\bar{1}\bar{1}00$)
4° / [$\bar{1}\bar{1}20$]	80	18	60	58
8° / [$\bar{1}\bar{1}20$]	60	30	56	54
15° / [$\bar{1}\bar{1}20$]	103	4	72	74
8° / [$\bar{1}\bar{1}20$]	49	46	14	68

Field effect channel mobility for each plane on 15 off-substrates

4. Patent available for licensing

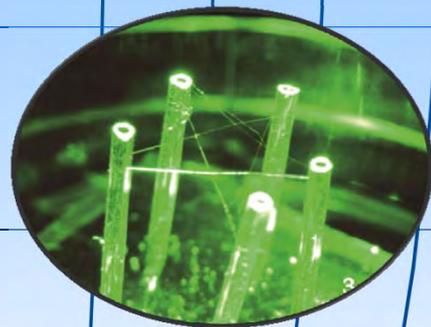
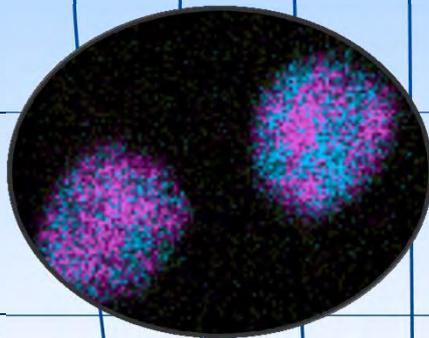
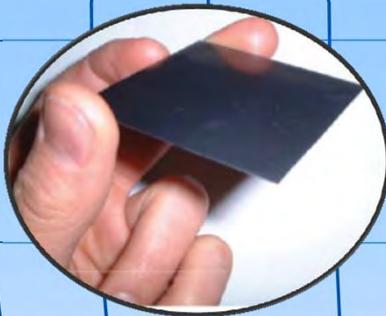
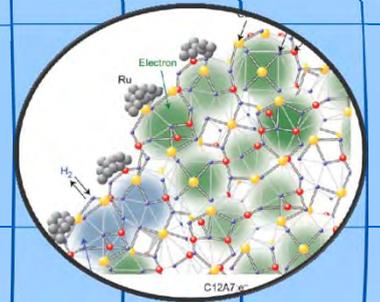
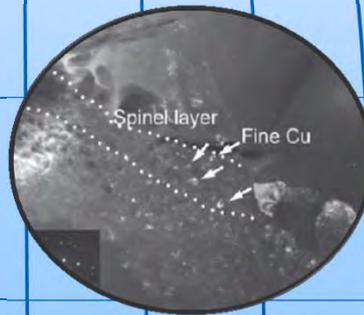
Patent No. : WO2012/026089
(JP,US,EP,KR,CN)

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$\{11\bar{2}0\}$ face tilted by 15° toward $[000\bar{1}]$

Advanced Materials

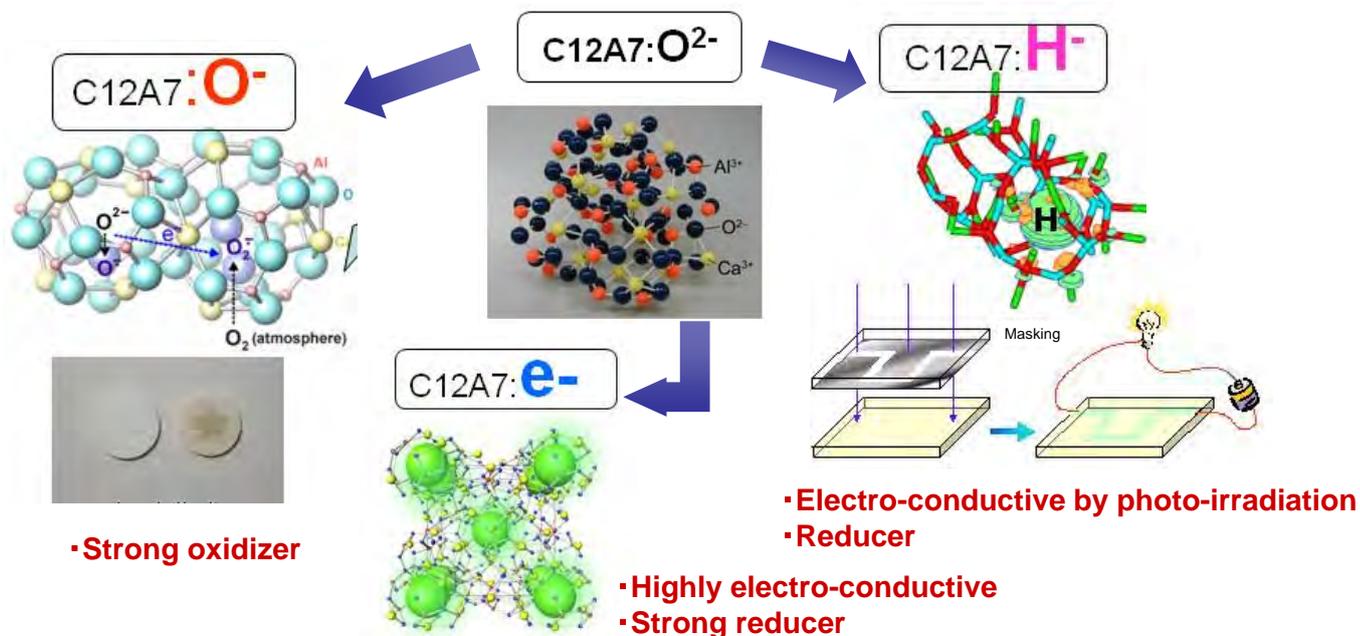


Electro-conductive & Transparent Nano-porous Compound C12A7

Prof. Hideo HOSONO (Tokyo Institute of Technology)

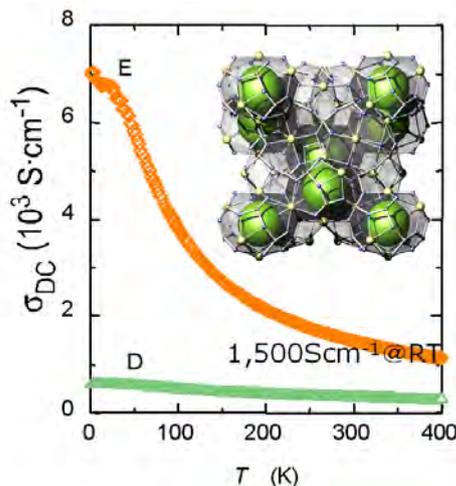
1. Novel Compound $12\text{CaO}\cdot 7\text{Al}_2\text{O}_3$ (i.e.C12A7)

- **C12A7** is composed of materials of alumina cements, and has 6 cages with an inner free space of 0.4nm of which only two cages are filled with O^{2-} . These 80% cages are free spaces.
- The oxide ions can be replaced by various anions such as O^- , H^- , OH^- , e^- etc. showing an **interesting function** for a variety of potential applications.

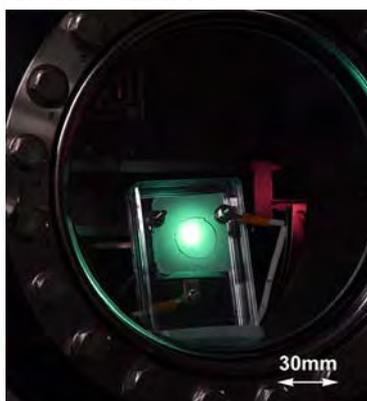


2. Electride C12A7: e⁻

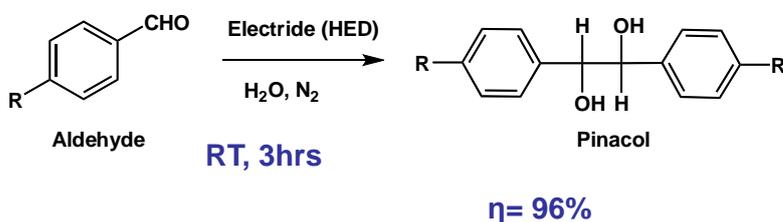
- **Conductivity of C12A7: e⁻**



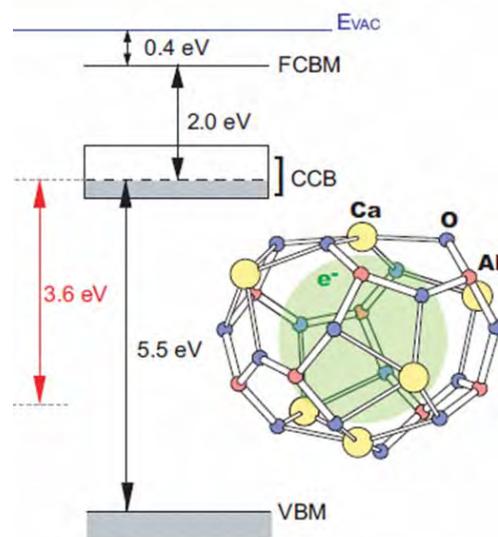
- **Cathode ray emission from C12A7: e⁻**



- **Reduction reaction using C12A7: e⁻**



3. Small work function of C12A7: e⁻



4. Patent available for licensing

Patent No. :US6818192,7462334.7235225,
7507289,7465433,
EP1717217,
JP4147324,4219821,4245608,
TW283234 etc

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NH₃ Synthesis using a Stable Electride C12A7 as Electron Donor and Reversible Hydrogen Store

Prof. Hideo HOSONO & Prof. Michikazu HARA (Tokyo Institute of Technology)

1. Present Industrial NH₃ Synthesis

- 160 million tons of NH₃ are produced each year through industrial processes at high temperature and high pressure.
- Iron based catalysts (Haber-Bosch method) or Ru metal particles dispersed on a support material in the industrial processes are used.



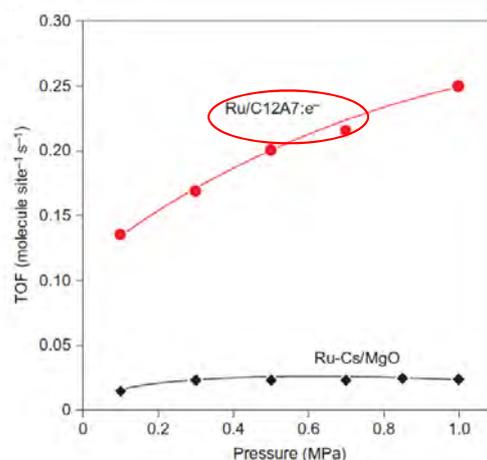
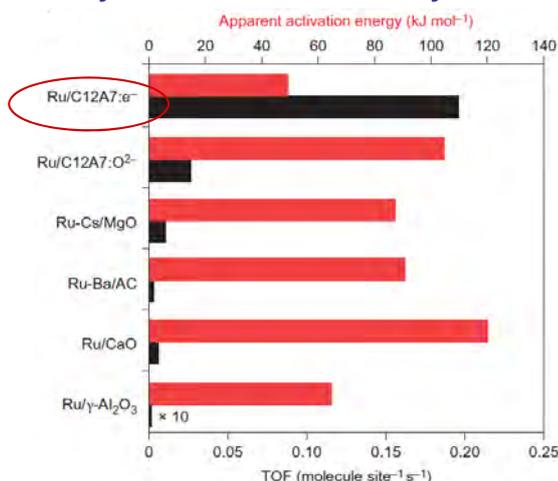
- The determining step is the **dissociation of both N₂ and H₂** on the metallic catalyst surface, and it is also important for the surface not to become covered by H₂ blocking active sites for N₂ dissociation (→H₂ **poisoning**).
- These processes consume a great deal of energy (around 1-2% of worldwide energy apply).



A novel supported Ru catalyst promotes N₂ & H₂ dissociation but suppresses H₂ poisoning, which will bring big energy savings.

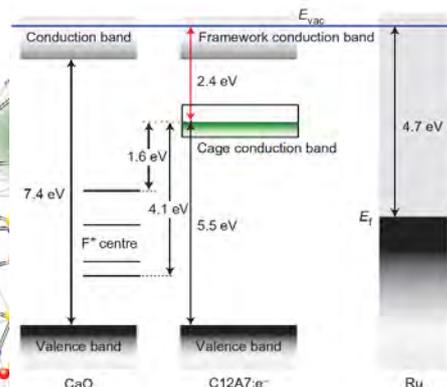
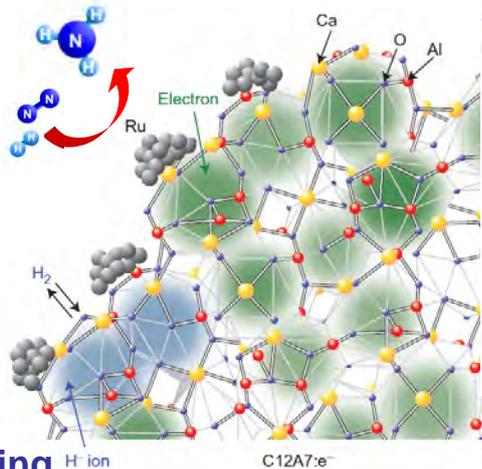
2. Catalytic Performance of Ru-loaded C12A7 Electride for NH₃ Synthesis

- Ru-loaded C12A7:e catalyst activity (TOF) shows one order magnitude greater than some current Ru catalysts. And also the catalyst exhibits the smallest activation energy.



3. Schematic Model of Ru-loaded C12A7 Electride in NH₃ Synthesis

- N≡N bond becomes weakened by electron donating from C12A7:e to the N₂ anti-bonding orbital.
- The C12A7:e also has the role of H₂ scavenger, and transforms H atom to hydride which is reversibly incorporated into the C12A7 nanocages.



4. Patent available for licensing

Patent No. : WO/2012/077658
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Newly developed H₂ Generator using Highly-Oxygen-Permeable Ceria-based Membrane

Prof. Hiroshi TAKAMURA (Tohoku Univ.)

1. Advantages of MPOX (Partial Oxidation of Methane by using Oxygen Permeable Membranes)

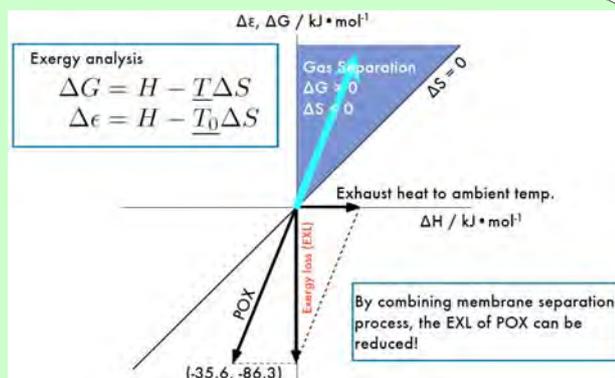
- Objective : Hydrogen generation from natural gas
- Comparison of candidate reaction

	Reaction Formula	ΔG^0_{298} (kJ/mol)	ΔH^0_{298} (kJ/mol)	ΔS^0_{298} (kJ/mol)	drawbacks
Steam reforming	$\text{CH}_4 + \text{H}_2\text{O} \rightarrow \text{CO} + 3\text{H}_2$	150.843	250.176 (endothermic)	333.164	Slow Start-Ups: Approx. 1h
Partial oxidation	$\text{CH}_4 + 1/2\text{O}_2 \rightarrow \text{CO} + 2\text{H}_2$	-86.347	-35.654 (exothermic)	170.024	Large Exergy Loss

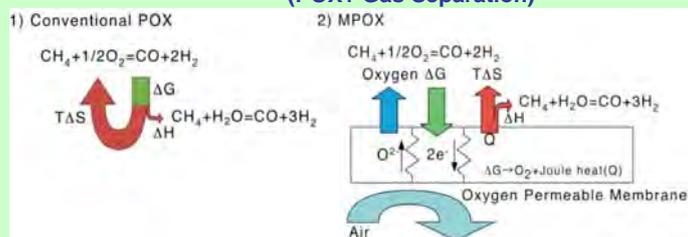
- Partial Oxidation of Methane (POX)
- Can Large Exergy loss (EXL) of POX be reduced?

Exergy Analysis
Combination with the reaction with exergy vector having opposite direction to POX is promising.

- MPOX : Membrane separation process + POX ($\Delta G > 0, \Delta S < 0$)
- Reduction of EXL of POX is achieved.



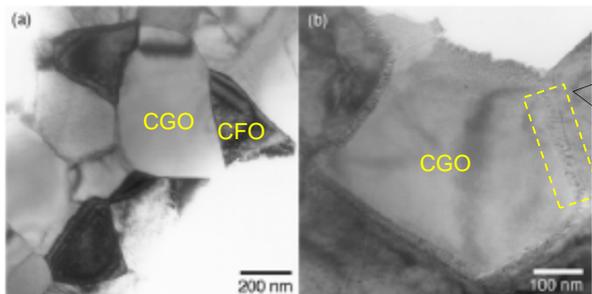
Exergy Analysis shows the advantage of MPOX (POX+ Gas Separation)



MPOX effectively utilizes the free energy generated from partial oxidation reaction to Oxygen separation

2. Ceria-based oxygen permeable membranes

	Composition	Oxygen flux density $\mu\text{mol} \cdot \text{cm}^{-2} \cdot \text{s}^{-1}$	Temp. °C	Ref.
BSCF	$\text{Ba}_{0.5}\text{Sr}_{0.5}\text{Co}_{0.9}\text{Fe}_{0.2}\text{O}_3$	8.6	875	Shao <i>et al.</i> , 2001
LSGF	$\text{La}_{0.7}\text{Sr}_{0.3}\text{Ga}_{0.6}\text{Fe}_{0.4}\text{O}_3$	8.2	1000	Ishihara <i>et al.</i> , 2002
PSAF	$\text{Pr}_{0.7}\text{Sr}_{0.3}\text{Fe}_{0.8}\text{Al}_{0.2}\text{O}_3$	8.2	1000	Takamura <i>et al.</i> , 2002
Ceria-MFO	$(\text{Ce}, \text{Sm})\text{O}_{2-15}\text{vol}\%\text{MnFe}_2\text{O}_4$	10.0	1000	Takamura <i>et al.</i> , 2002
LBSFI	$(\text{La}_{0.5}\text{Ba}_{0.5}\text{Sr}_{0.2})(\text{Fe}_{0.6}\text{In}_{0.4})\text{O}_3$	10.6	1000	Aizumi <i>et al.</i> , 2004

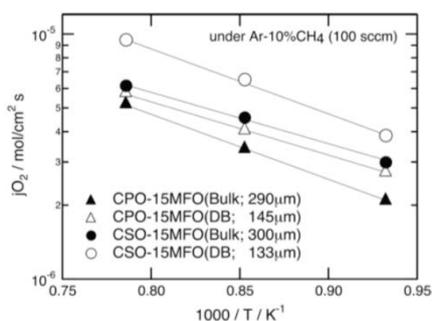


Grain boundary
• nano-sized CGO
• spinel-type ferrite grains.

Ceria-MFO: $(\text{Ce}, \text{Gd})\text{O}_{2-17}\text{vol}\%\text{CoFe}_2\text{O}_4$ fired at 1300°C for 2 h



CSO membrane made by tape-casting technique: 5cm x 5cm



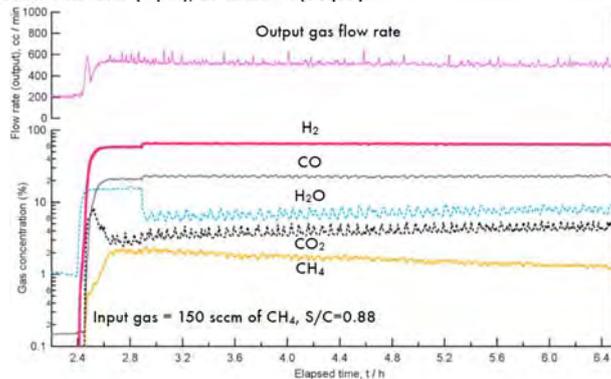
Oxygen permeation properties

- Ceria-MFO: $(\text{Ce}, \text{Re})\text{O}_2 + \text{MeFe}_2\text{O}_4$
- $(\text{Ce}, \text{Re})\text{O}_2$: Oxygen Conductive Phase (Re is an acceptor) (CGO (Re=Gd), CSO (Re=Sm) and CPO (Re=Pr))
- MeFe_2O_4 : Electron Conductive Phase

3. Characteristics of MPOX reformer

No. of modules	CH ₄ (sccm)	Air (sccm)	Temp. (°C)	S/C	jO ₂ ($\mu\text{mol}/\text{cm}^2 \cdot \text{s}$)	CH ₄ conv. (%)	CO selectivity (%)	H ₂ selectivity (%)
1	150	500	780	0.88	3.3	96	84	89

*C-balance: 150 sccm (input); 151.8 sccm (output)



Flow rate and composition of reformat gas



MPOX reformer module comprising of CSO.15MFO and ZMG232R (left) and its 20 stacks (right)

To produce 10 liter/min of hydrogen, stack of 20 modules is required.

4. Patent available for licensing

Patent No. : WO/2003/084894, WO/2007/046314 (JP,US,EP)

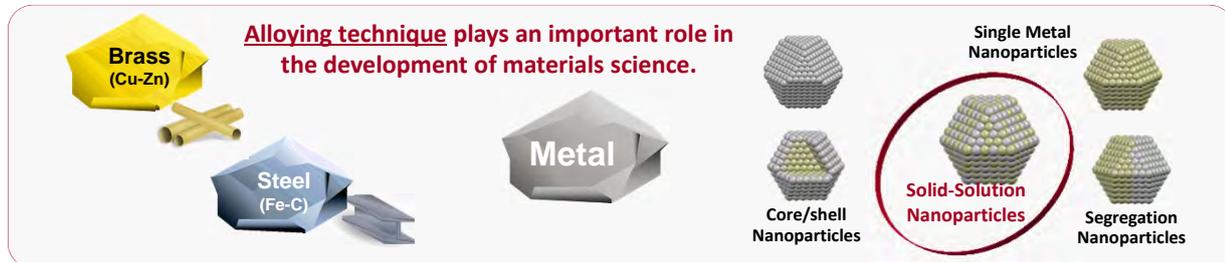
Contact : Takuji OHINATA (JST)
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PdRu Solid-Solution Alloy Nanoparticles with Enhanced CO Oxidation Activity

Prof. Hiroshi KITAGAWA (Kyoto University)

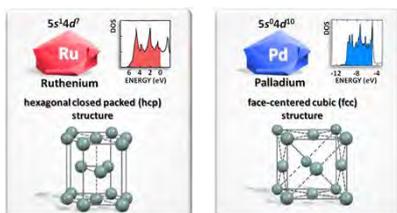
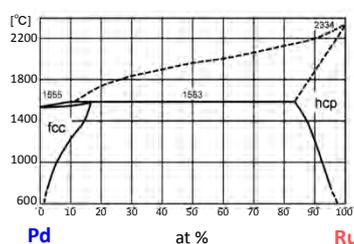
1. Solid-Solution Alloy

- Mixed metal at the atomic level
- Have the advantage of easily controlling chemical and physical properties by changing compositions and/or combinations

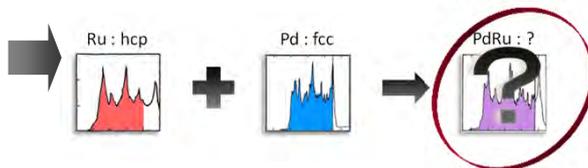


However...

Solid-solution phases are limited by combinations, compositions and/or temperature.

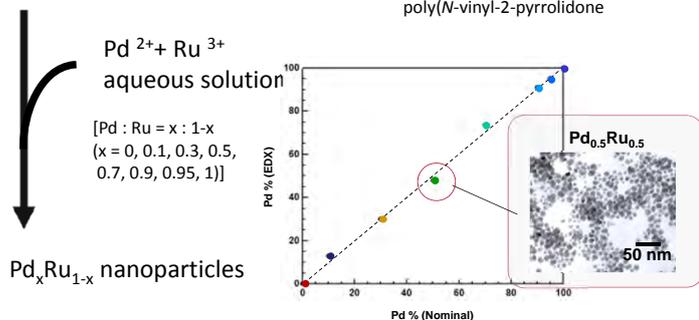


PdRu solid-solution alloys had not yet obtained....

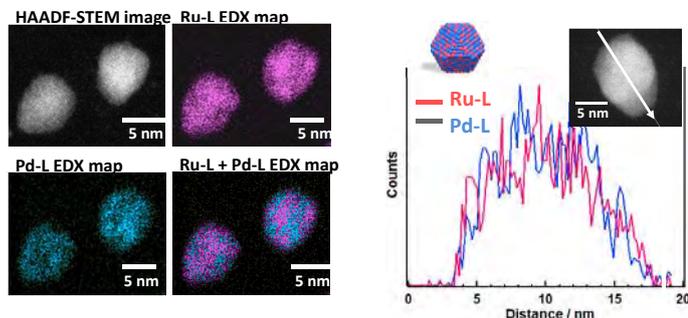


2. NOVEL Synthesis Process

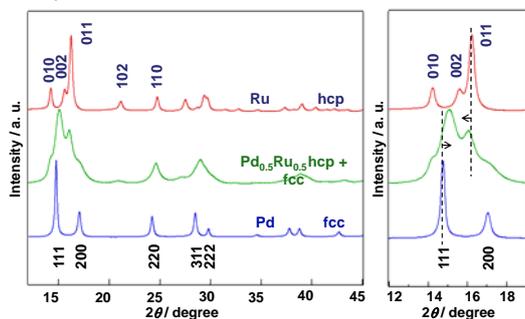
Triethyleneglycol (Reducing agent) + PVP (Protecting agent)
poly(N-vinyl-2-pyrrolidone)



- Elemental Mapping Images of Pd_{0.5}Ru_{0.5} NPs
- Compositional Line Profiles

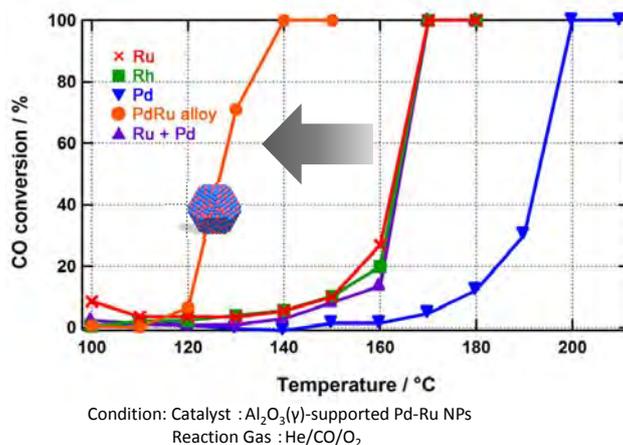


- Powder X-ray Diffraction (XRD) Patterns



3. CO Oxidation Catalyst

- The Pd-Ru solid-solution alloy oxidizes carbon monoxide at much lower temperature..



The Pd-Ru solid-solution alloy performs significantly higher activity than any of other metal nanoparticles in single phase, so it is expected to serve as a high-performance catalyst surpassing the conventional catalysts.

4. Patent available for licensing

Patent No. : JP2012-204292

(International application is in preparation.)

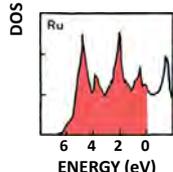
Contact : Miho OKISHIRO (JST)
phone: +81-3-5214-8486
e-mail: license@jst.go.jp

Ru Nanoparticles with fcc Structure for High-activity Catalyst

Prof. Hiroshi KITAGAWA (Kyoto University)

1. Ruthenium Nanoparticles

26 Fe	27 Co	28 Ni	29 Cu
44 Ru	45 Rh	46 Pd	47 Ag
76 Os	77 Ir	78 Pt	79 Au



Ruthenium is extensively used as catalyst:

- Organic synthesis
- CO removal from car exhaust or fuel-cell systems

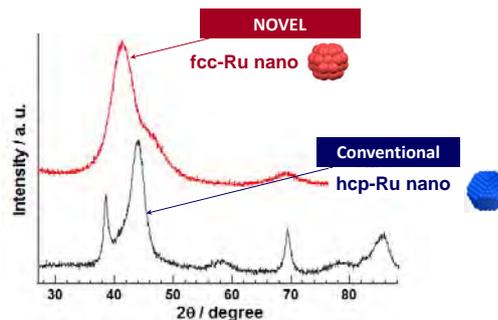
However, the conventional synthesis process results in merely the **hcp-Ru**, meaning that there was no convenient way able to produce **fcc-Ru nanoparticles**.

This study successfully meet the demand for synthesizing fcc-Ru nanoparticles, serving as high-active catalyst.

fcc : face-centered cubic
hcp : hexagonal closed packed structure

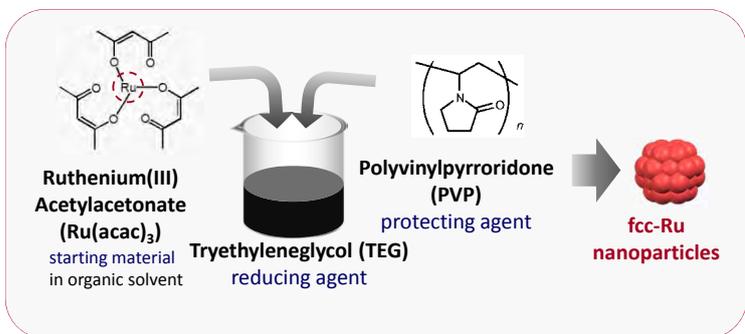


Application example "ENE-FARM" : Ru catalyst is used within the household fuel-cell cogeneration system.

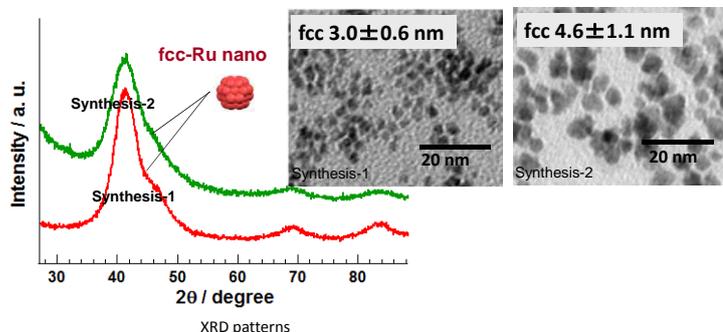


2. NOVEL Synthesis Process

- Substantial fcc-Ru nanoparticles
- Single-step synthesis
- Particle size controllable

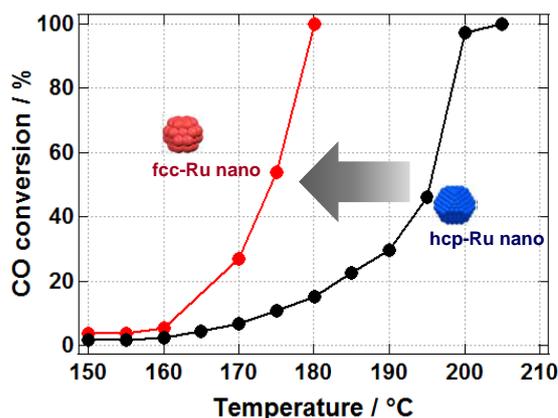
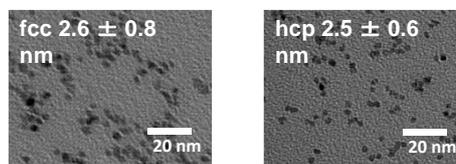


Particle size is controllable by varying the synthesis condition.



3. CO Oxidation Catalyst

- The fcc-Ru catalyst oxidizes carbon monoxide at lower temperature than hcp-Ru catalyst.



Condition: Catalyst Quantity : 0.075 g, $\text{Al}_2\text{O}_3(\gamma)$ -supported Ru
Reaction Gas : He/CO/ O_2 = 49/0.5/0.5 (cc/min)
Reaction temperature : 150 °C ~

4. Patent available for licensing

Patent No. : PCT/JP2012/005838
(JP, US)
Contact : Miho OKISHIRO (JST)
phone:+81-3-5214-8486
e-mail: license@jst.go.jp

The fcc-Ru catalyst, firstly prepared by the novel synthesis process, performs significantly higher activity than the hcp-Ru catalyst.

Application of Leached Al-Cu-Fe Quasicrystal to Steam Reforming of Methanol

Prof. An-Pang TSAI (Tohoku University)

1. Motivation to Catalytic Application of QC

- So far, research on quasicrystals (QCs) has been purely academic.
- What is found as general physical properties of QCs are:

- 1) Thermodynamically stable
- 2) Stable up to high temperature
- 3) Very brittle ... easy to obtain powder form by crushing
- 4) High-specific surface area
- 5) Extreme high resistivity : a few thousand of $\mu\Omega\text{cm}$
- 6) Hardness comparable to silica : 800~1000Hv
- 7) Low friction coefficient comparable to Diamond

Application to Catalyst is promising.

Candidate Materials:



- Al, Cu, Fe : abundant and cheap
- Cu : various catalytic behavior

2. Catalyst preparation to SRM reaction

(1) Precursor Quasicrystal Preparation

Al-Cu-Fe QC alloy ingots
(prepared in Argon atmosphere in arc furnace)

Annealing: 24h at 800°C

Crushing and Screening

Precursor Quasicrystal with size 20~53 μm

(2) Catalyst Preparation

Alkali leaching by 5wt% NaOH aqueous solution for 4h room temperature to remove Al

Filtered out and washed with distilled water

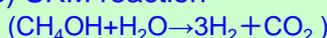
Dried at 50°C overnight

Leached Powder (before Calcination) ... (a)

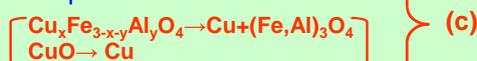
Calcined at 600°C for 3h in air

Calcined QC powder ... (b)

(3) SRM reaction



Activation in H_2 atmosphere at 200~300°C

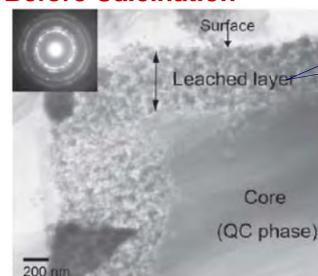


Steam Reforming Reaction (SRM)

(Reduction of Catalyst by H_2 generated from SRM reaction occurs)

3. Structural Changes: TEM image

(a) Before Calcination



Homogenous mixture of oxides containing Cu, Fe, Al

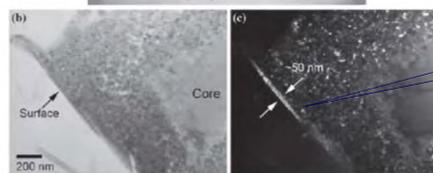
• BFI of cross-section of QC before Calcination (Insert electron pattern obtained from the leached layer)

(b) After Calcination



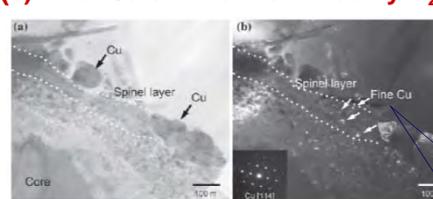
a) BFI of cross-section of NaOH leached Al-Cu-Fe QC alloy after calcination at 600°C

b) BFI around the leached layer
c) DFI using 2-20 reflection of cubic spinel at the surface,



Spinel Layer: $\text{Cu}_x\text{Fe}_{3-x-y}\text{Al}_y\text{O}_4$

(c) After Calcination followed by H_2 reduction



a) BFI of leached area of NaOH-leached Al-Cu-Fe QC alloy after calcination at 600°C followed by H_2 reduction at 300°C

b) DFI using 2-20 reflection of Cu.

Fine Cu: key factor for catalytic activity enhancement

4. Physical Properties and Catalytic Activities

Catalyst	Cu crystallite size ^b (nm)	BET surface area (m ² /g _{cat})	N ₂ O titration ^d (μmol/g _{cat})	H ₂ production rate ^e			CO selectivity ^g (%)
				per catalyst weight (μmol/s/g _{cat})	per surface area (μmol/s/m ² _{cat})	per N ₂ O titration (μmol/s/μmol(N ₂ O))	
Leached QC	21	20.0	116.8	306.9	15.3	2.63	1.3 (b)
Leached QC with calcination	31 (10 ^f)	5.0	126.6	405.0	81.0	3.20	1.2 (c)
Cu/ZnO ^h	10	57.3	262.2	372.2	6.5	1.42	1.5
CuO	66	2.4	12.2	15.4 : small	6.4	1.26	-
CuFeAlO ₄	13	1.7	67.7	242.2 : large	142.4	3.58	1.2

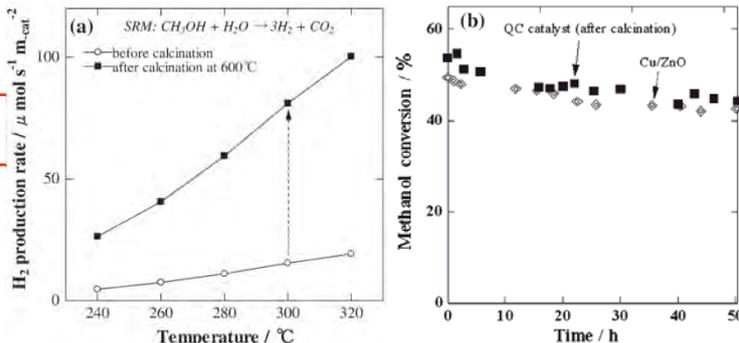
• Cu/ZnO : commercial SRM catalyst

• Both CuO and CuFeAlO₄ reside in calcined QC.

5. Patent available for licensing

Patent No. : 7592292(US), 284059(TW)
(EP, JP (under examination))

Contact : Takuji OHINATA (JST)
phone: +81-3-5214-8486, e-mail: license@jst.go.jp



Abbreviations BFI : Bright Field Image of TEM
DFI : Dark Field Image of TEM
SAED : Selected Area Electron Diffraction
SRM : Steam Reforming of Methanol

Two Types of Ferrous Polycrystalline Shape-Memory Alloys Showing Superelasticity (FeNiCoAlTaB, FeMnAlNi)

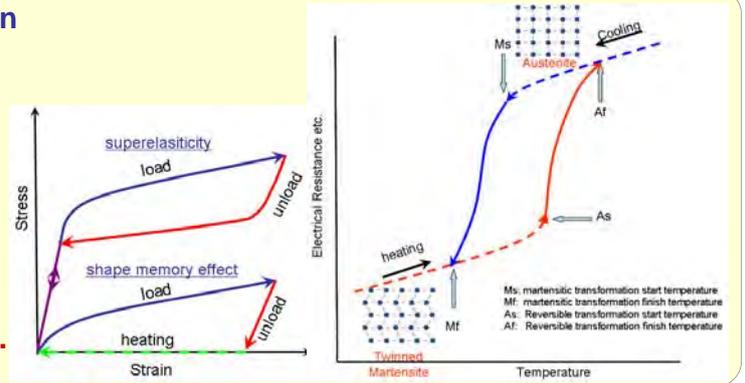
Prof. Ryosuke KAINUMA,
Asst. Prof. Toshihiro OMORI (Tohoku University)

1. The Ways to Give Superelasticity to SMAs

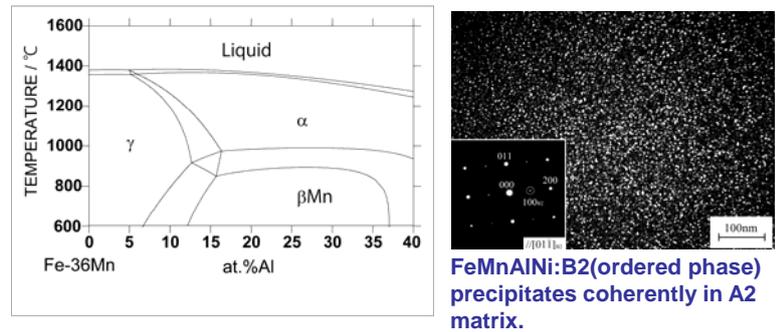
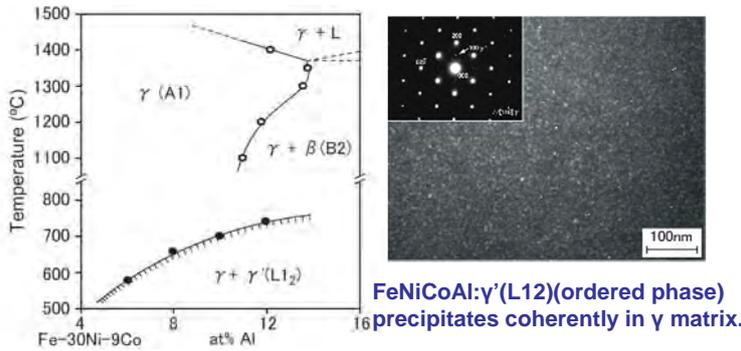
- Shape Memory Effect ... heating is required to return to original state (original shape).
- Superelasticity ... heating is **not** required to return to original state (elastic deformation).

↓
● Martensitic transformation should be thermoelastic to gain superelasticity.

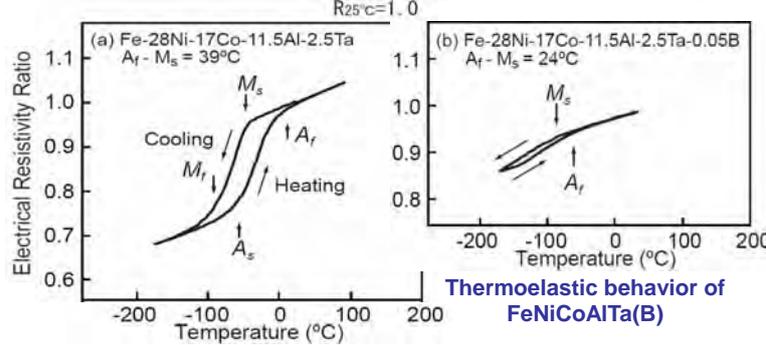
↓
● Introduction of (partially) ordered phase is required.



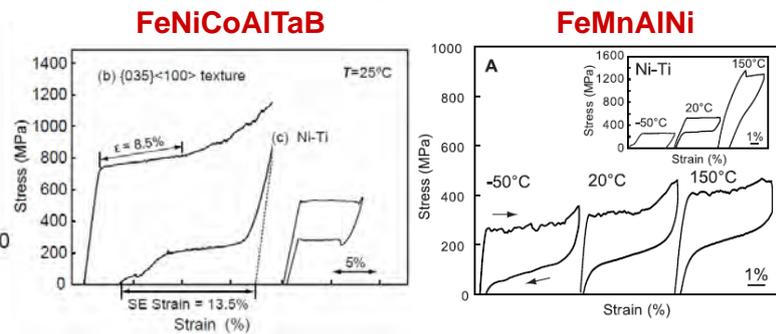
2. Alloy Design of FeNiCoAl and FeMnAl alloys with ordered precipitates



3. Thermoelasticity (only for FeNiCoAl)

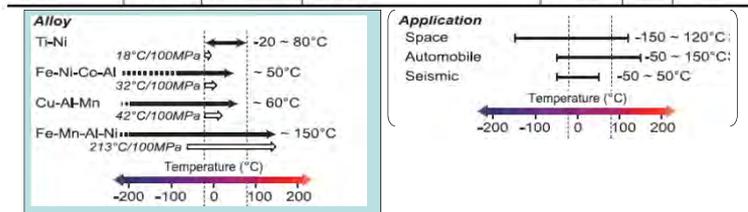
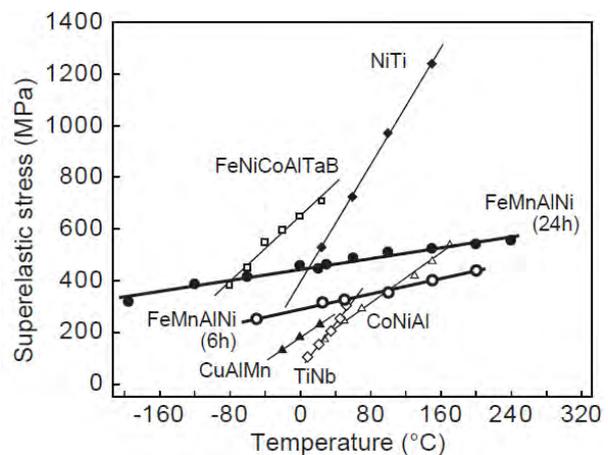


4. Superelastic Properties



5. Comparison with Conventional Metal Alloys

Alloy system	Crystal structure		Chemical composition (at%)	ΔS (J mol ⁻¹ K ⁻¹)	ϵ_{SE} (%)	$\frac{d\sigma_e}{dT}$ (MPa °C ⁻¹)
	Parent	Martensite				
Fe-Mn-Al-Ni	BCC (A2+B2)	FCC	Fe _{43.5} Mn ₂₁ Al ₁₀ Ni _{7.5}	-0.43	5.2	0.53
Fe-Ni-Co-Al	FCC	BCT	Fe _{40.95} Ni _{12.6} Co ₁₇ Al _{11.5} Ta _{2.5} B _{0.05}	-2.95	13.5	3.1
Ti-Ni	B2	B19'	Ti ₅₀ Ni ₅₀	-4.37	7.3	5.7
Ti-Ni-Cu	B2	B19	Ti ₅₀ Ni ₄₀ Cu ₁₀	-2.92	3.2	8.4
Cu-Al-Ni	D0 ₃	6M	Cu _{68.4} Al _{27.8} Ni _{3.8}	-1.03	8.6 [†]	1.5 [†]
		20		-1.20	4.7 [†]	3.4 [‡]
Cu-Zn-Al	D0 ₃	6M	Cu _{67.9} Zn _{16.1} Al ₁₆	-1.45	8.5 [†]	2.1 [‡]
Cu-Al-Mn	L2 ₁	6M	Cu _{71.9} Al _{10.6} Mn _{9.3} Ni ₂ B _{0.2}	-1.15	7.5	2.4
Ni-Mn-Ga	L2 ₁	10M	Ni ₅₂ Mn _{24.4} Ga _{23.6}	-0.97	4.0 [†]	3.5 [†]
Ni-Fe-Ga	L2 ₁	14M	Ni ₅₁ Fe ₂₂ Ga ₂₇	-0.91	6.2 [†]	1.9 [†]
Ti-Nb	BCC	Orthorhombic	Ti ₇₄ Nb ₂₆	-1.30	2.3	4.4



6. Patent available for licensing

Patent No. : WO2007/055155, WO2011/046055 (JP, US, EP, CN, KR, CA)
Contact : Takuji OHINATA (JST)
phone: +81-3-5214-8486
e-mail: license@jst.go.jp

Cobalt-Based High-Temperature Alloys

Prof. Emeritus Kiyohito ISHIDA,
Asst. Prof. Toshihiro OMORI (Tohoku University)

1. Beyond Ni-based Superalloys

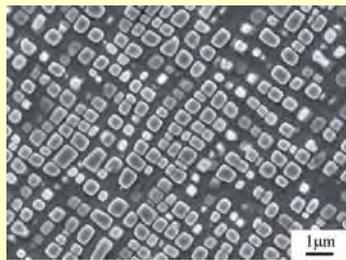
- Co-based alloys' properties as superalloys candidate (compared to Ni-based superalloys)

- Higher melting point ... favorable
- Lower strength ... unfavorable

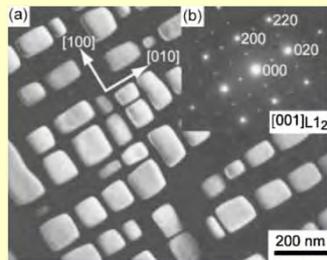
↓ Precipitation hardening of matrix by ordered phase is necessary as in the case of Ni-based superalloys.

- $\gamma+\gamma'$ phase in Co-Al-W was discovered

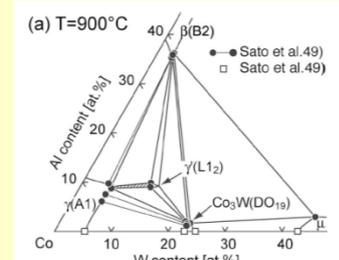
Co-Al-W superalloys



Phase of Newly developed Co-Al-W alloys

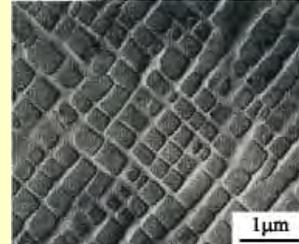


Precipitated phase was confirmed as γ' phase



Phase diagrams of the Co-Al-W ternary system

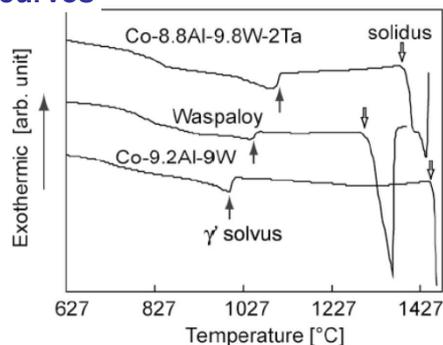
Ni-based superalloys



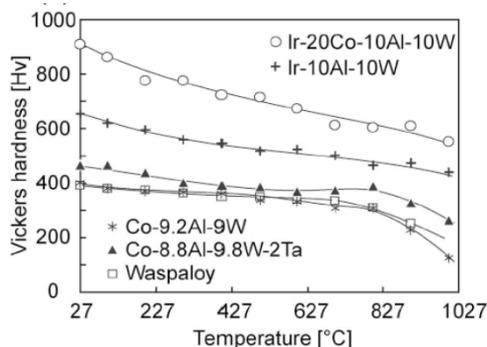
$\gamma+\gamma'$ phase in Ni-based superalloys for comparison

2. Properties of New Alloys

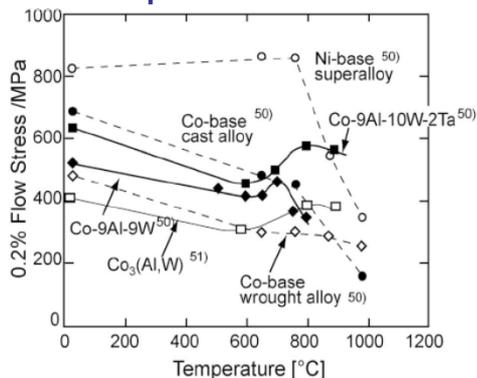
(a) DSC curves



(b) Vickers Hardness of various alloys



(c) Temperature dependence of 0.2% Flow Stress



3. Application Examples

(1) High hot-workability



Hot rolling at 1,250°C



(2) Application to a Friction-Stir-Welding tool



Before Welding



After Welding



Welded Sample (Two Ti plates are welded)

4. Patent available for licensing

Patent No. : WO2007/032293, WO2007/091576
(JP,US,EP,CN,CA)

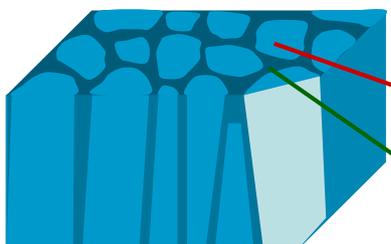
Contact : Takuji OHINATA (JST)
phone: +81-3-5214-8486
e-mail: license@jst.go.jp

Excellent Mechanical Properties of Hybridized Carbon Nano-composite Thin Films

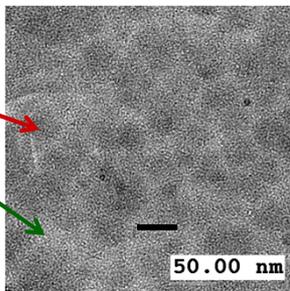
Dr. Eiji IWAMURA (Arakawa Chemical Ind. Ltd. formerly, University of Tokyo)

1. Fabrication of Hybridized Carbon Films

- **Sputtering method** is used under the conditions of both low temperature of substrate and high pressure of atmosphere gas for fabrication of **network structures consisting of columns and inter-column regions in a-C films**.



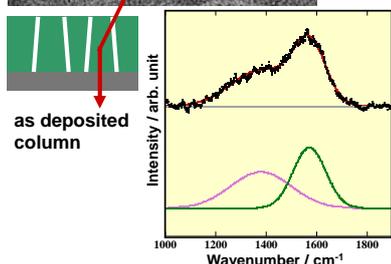
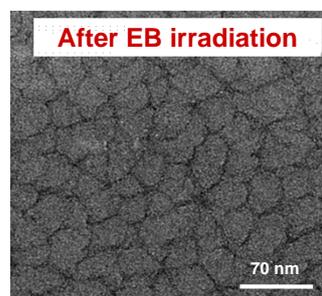
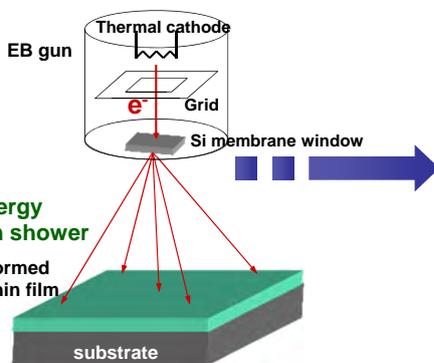
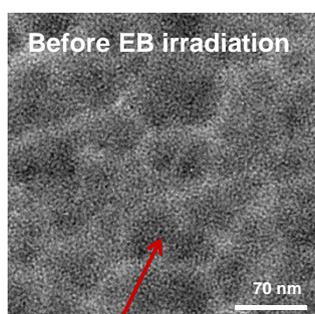
Column regions : $d=1.8 \text{ g/cm}^3$
Inter-column regions : $d=1.6 \text{ g/cm}^3$



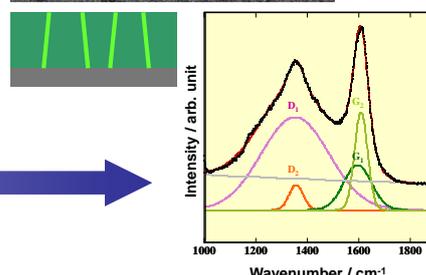
Hybridized a-C film :

- Thickness: 500 nm
- Sputtered deposited on Si wafer
- Substrate : Room temp.
- Ar+CH₄ gas pressure: 4Pa

2. Structural Modification by Low-energy EB Irradiation



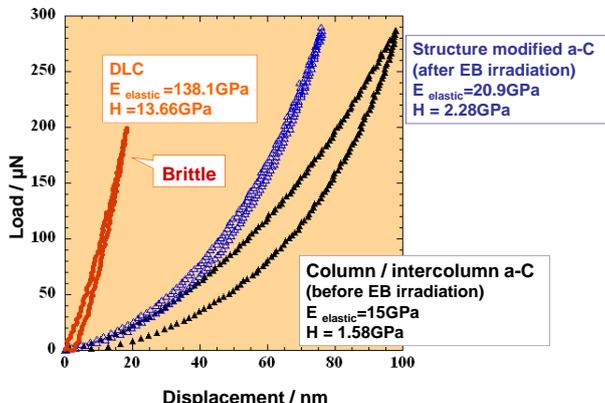
Graphitization induced by EB irradiation



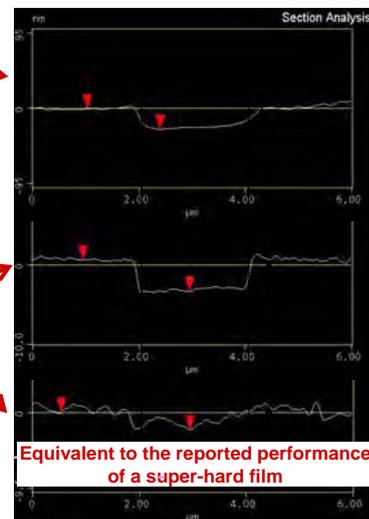
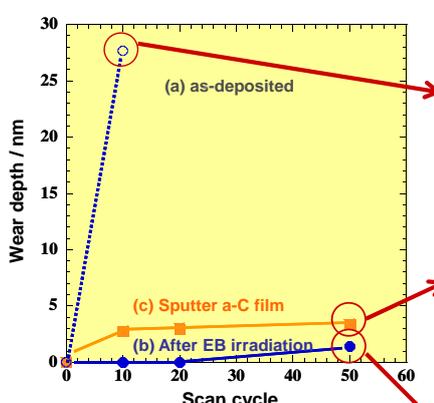
3. Mechanical Properties of EB Irradiated Film

- EB irradiated film shows not only superior wear resistance but also high elasticity.

● Film Hardness : Nanoindentation Test



● Micro-wear Resistance Test



Equivalent to the reported performance of a super-hard film

4. Patent available for licensing

Patent No. : WO/2005/083144
Contact : Masaru OZAKI (JST)
phone: +81-3-5214-8486
e-mail: license@jst.go.jp

Hydrogen Storage Material using Hybridized Carbon Nano-composite

Dr. Eiji IWAMURA (Arakawa Chemical Ind. Ltd. formerly, University of Tokyo)

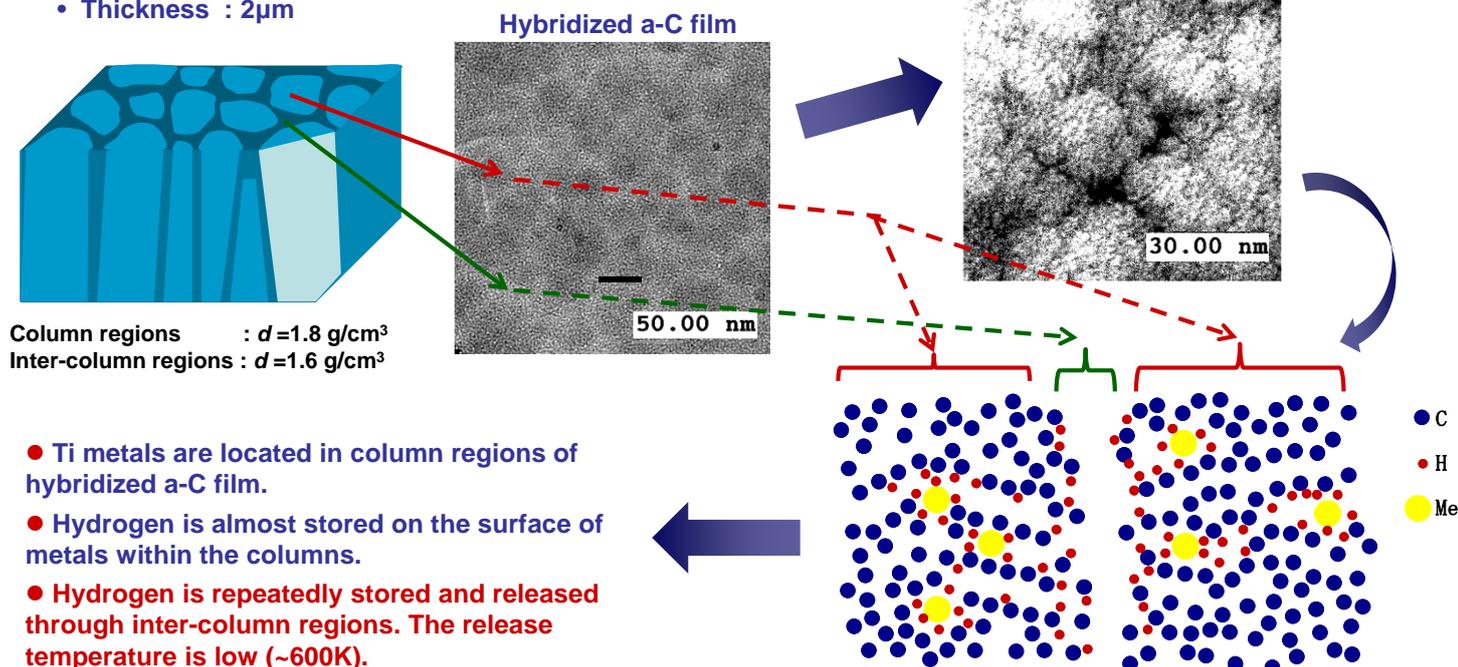
1. Fabrication of Hybridized Carbon Films including Metal (ex. Ti, Y, Zr, Hf)

- **Sputtering method** with two target materials (graphite and metal) is used.
- **Metals are located in the column regions** in network carbon structures (columns and inter-column regions) of a-C films.

Fabrication condition of hybridized a-C film including metal

- Targets : Graphite and metal (e.g. Ti , Y, Zr, Hf)
- Sputter deposited on Si wafer
- Substrate temp. : Room temp.
- Ar gas pressure : 2 Pa
- Thickness : 2 μ m

Hybridized a-C film including Ti metal
(White color part is Ti metal.)



- Ti metals are located in column regions of hybridized a-C film.
- Hydrogen is almost stored on the surface of metals within the columns.
- Hydrogen is repeatedly stored and released through inter-column regions. The release temperature is low (~600K).

2. Characteristic Table of Storing / Releasing Hydrogen

Metal	w%	Substrate Temp. (K)	Ar pressure (Pa)	Release Temp. (K)	H ₂ stored initial volume (atm%)	H ₂ stored volume after 5 cycles (atm%)
None	0	283	1.99983	600	2.0	5.0
Ti	12.5	283	1.99983	600	14.0	13.0
Y	3.0	283	1.99983	600	16.0	16.0
Zr	8.0	283	1.99983	600	13.6	13.2
Hf	26.0	283	1.99983	600	12.5	10.8

3. Patent available for licensing

Patent No. : WO/2004/067166
(JP,US,EP,KR,CN)
Contact : Masaru OZAKI (JST)
phone: +81-3-5214-8486
e-mail: license@jst.go.jp

Template Synthesis in Hydrodynamically-Aligned Supramolecular Nano-channels

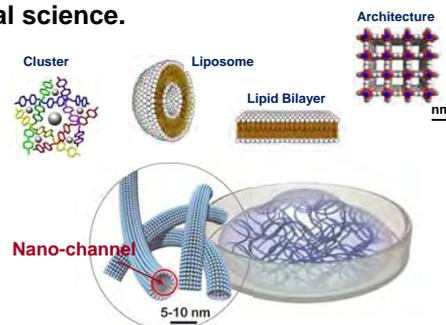
Dr. Daisuke KIRIYA, Dr. Hiroaki ONOE, et.al (Takeuchi Lab, University of Tokyo)

1. Hydrodynamically-Aligned Supramolecular Nano-channels

- Supramolecular assembly has been essential from material science to biological science.
- Nanochannel** is expected as a nano-scale reaction vessel.

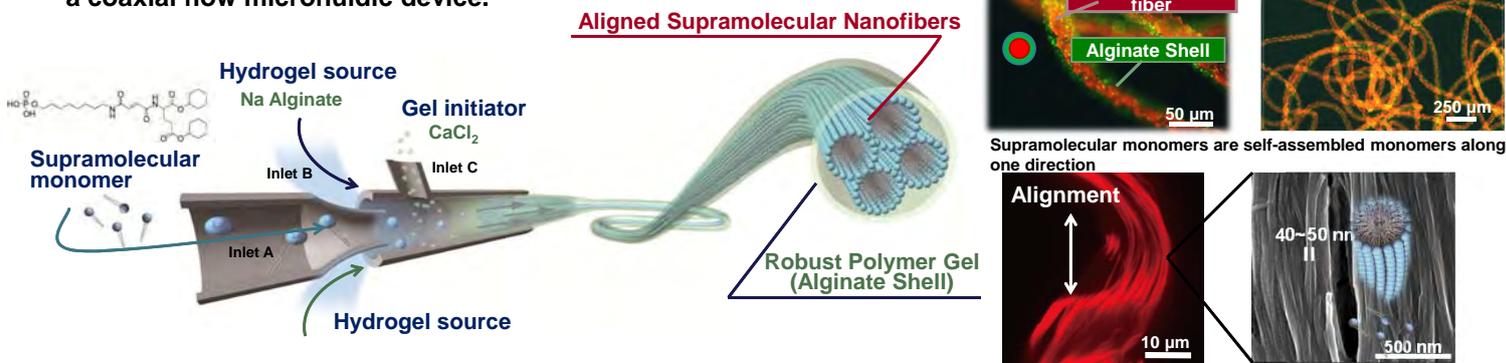
Two problems to solve

- Entanglement of supramolecular nanofibers
 - Need to prevent entanglement by using "Microfluidics"
- Poor handle-ability because of low mechanical strength
 - Need to increase mechanical strength by encapsulation in a robust polymer



2. Synthetic Process

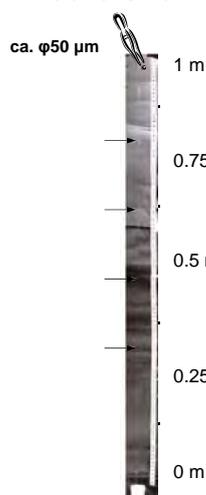
- Linearly-aligned Jacketed supramolecular fibers are fabricated in a coaxial flow microfluidic device.



3. Handling of Supramolecular Nanofibers

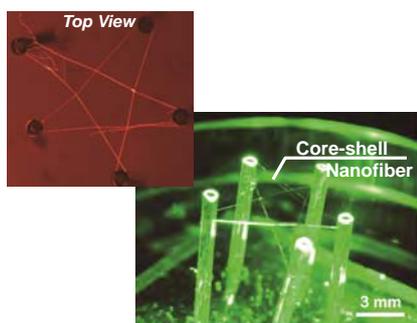
- Appropriate features for practical applications
 - Aligned supramolecular nanofibers
 - Easy-to-handle core-shell nanofibers

Meter-long core-shell fiber



Sufficient strength

A single jacketed supramolecular nanofiber bridging five glass pillars to form a star shape in air



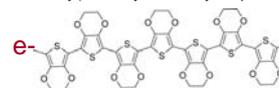
Potential applications
Scaffold for cell culture, Nano-scale reaction vessel

4. Synthesis as Reaction Vessels

- Template Synthesis in Hydrophobic Nano-Channels

PEDOT is extensively applied as a **conductive polymer**, however, its insolubility makes pure PEDOT difficult to handle.

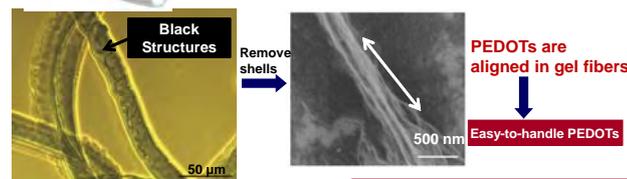
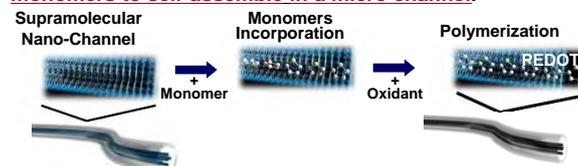
PEDOT Poly(3,4-ethylenedioxythiophene)



Potential applications
Biochemical molecules, proteins, nano-particles, metals for generating large oriented materials, etc.

Polymerization of PEDOTs

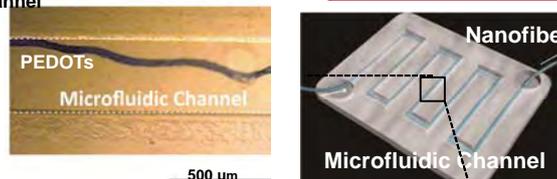
The process involves a step of causing **supramolecular monomers to self-assemble in a micro channel**.



Potential applications
Flexible organic circuits, Sensors

Example Application

PEDOTs incorporated in microfluidic channel

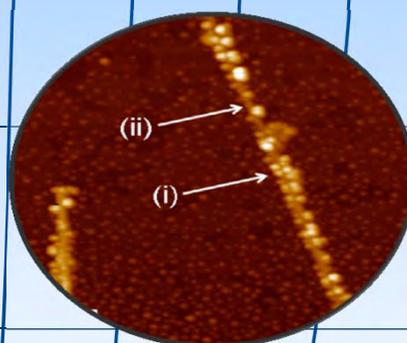
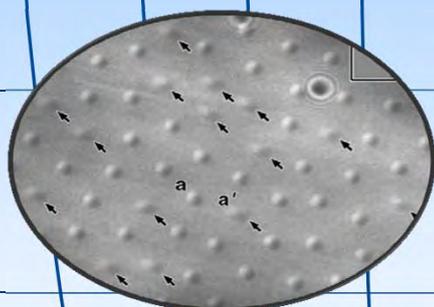
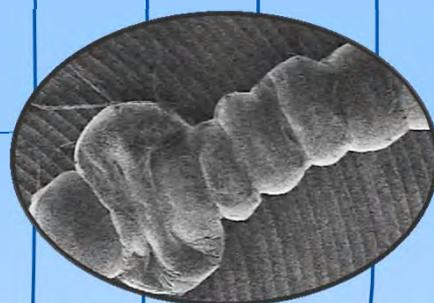
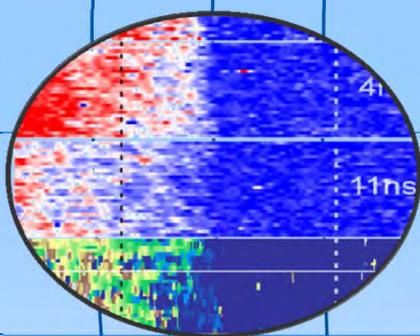
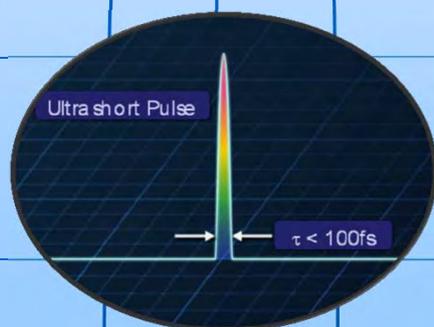


5. Patent available for licensing

Patent No. : WO/2011/089753
(US, JP)

Contact : Miho OKISHIRO (JST)
phone: +81-3-5214-8486
e-mail: license@jst.go.jp

Measurement Equipment

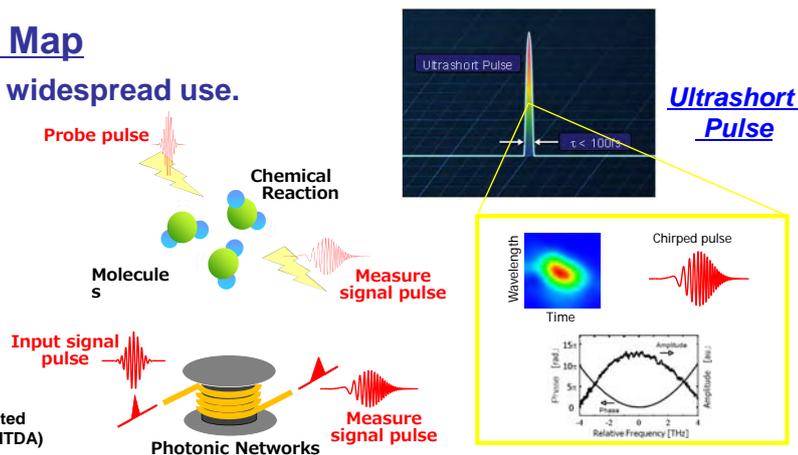
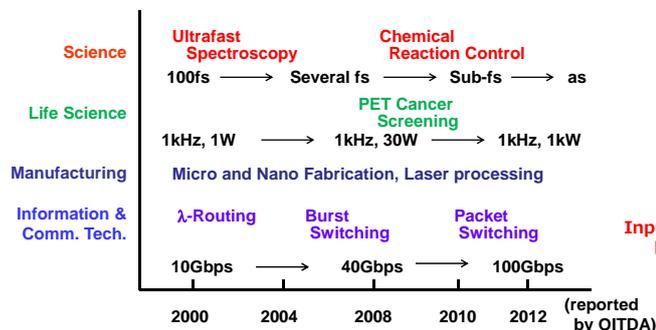


Very Simple Ultrashort Pulse Waveform Measurement and Reconstruction System

Prof. Tsuyoshi KONISHI(Osaka University)

1. Ultrashort Pulse Technology Load Map

- Simple Evaluation Technique is needed for widespread use.



2. Comparison of conventional Measurement technique of Ultrashort pulse

	This Technique	Auto Correlator	SHG-FROG
Measurement Time	⊙ Almost Real Time	⊙ Real Time	△ ~ 10 min.
Phase Retrieval	○	×	○
Ease of Handling	⊙	⊙	△
Sensitivity	○ fJ~mJ	○ fJ~mJ	○ fJ~mJ

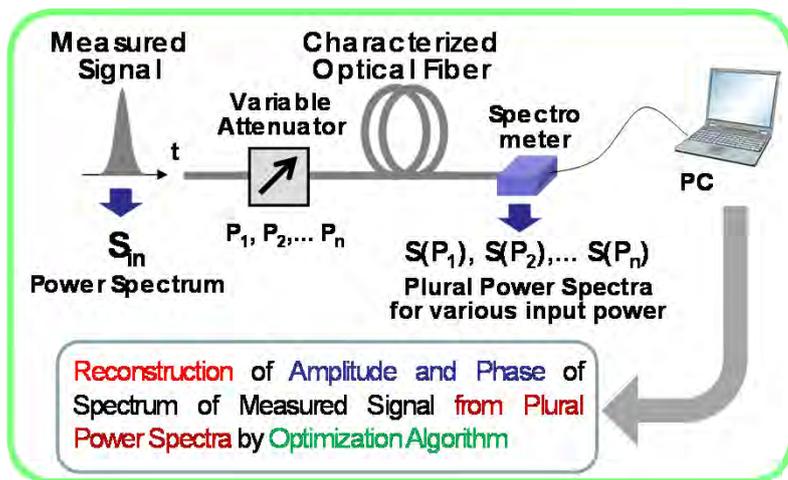
- A spectrometer is a simple and popular tool compared with commonly used measurement tools of ultrashort pulses.
- However, a spectrometer is not able to retrieve phase information of ultrashort pulses.



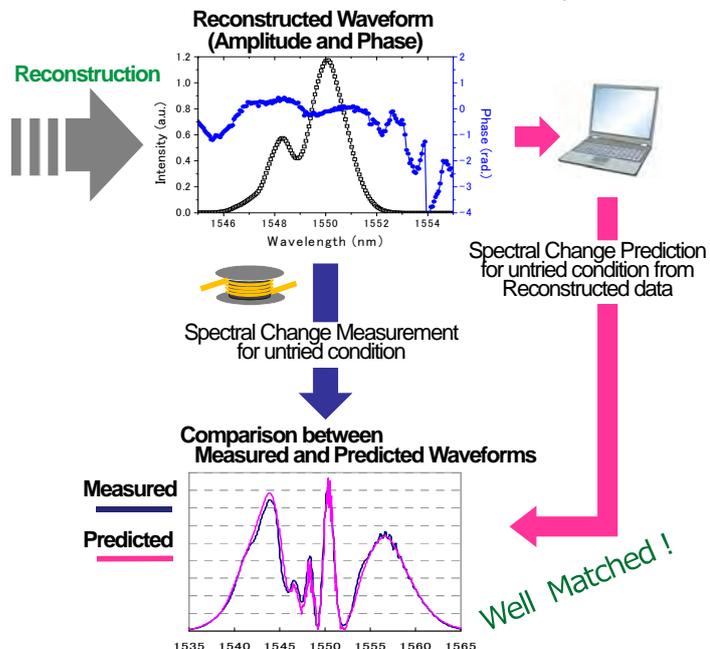
Our spectrometer-based approach allows retrieve phase information by using intensity-dependent spectral change and optimization algorithm.

3. Measurement and Reconstruction of Ultrashort pulse waveform

- System configuration



- Reconstructed Data and Its Accuracy



Detail of Procedure

- Measurement of power spectra $S(P_1) \sim S(P_n)$ for various input powers by a Spectrometer.
- Simulation of spectral change by propagation of an input optical signal through an optical fiber.
- Optimization of input ultrashort pulse waveform so that difference in value between the calculated and measured power spectra will be minimized.

4. Patent available for licensing

Patent No. : US2011-311223, JP2009-48608 (US, JP)

Contact : Hisahiro MORIUCHI (JST)
phone: +81-3-5214-8486
e-mail: license@jst.go.jp

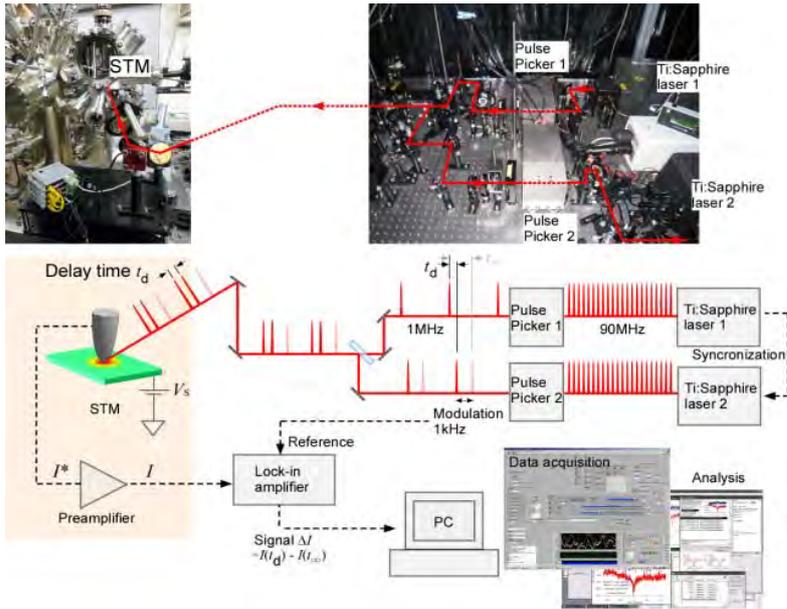
New Pump-probe Technique providing A Wide Range Time-scale and Nanoscale Measurement

Prof. Hidemi SHIGEKAWA (University of Tsukuba)

1. New Pump-probe Technique

● Delay time modulation femtosecond time-resolved scanning probe microscope

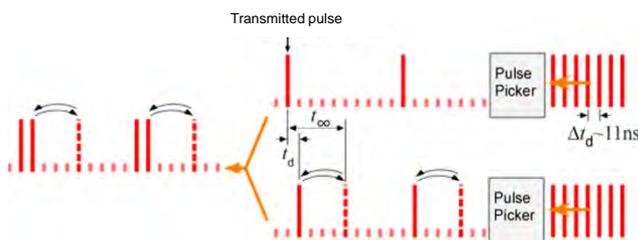
1. Wide-time range measurement (femtosec. – microse.)
2. Overcome of the thermal effect
3. Temporal resolution determined by pulse width and spatial resolution determined by STM



2. New key method

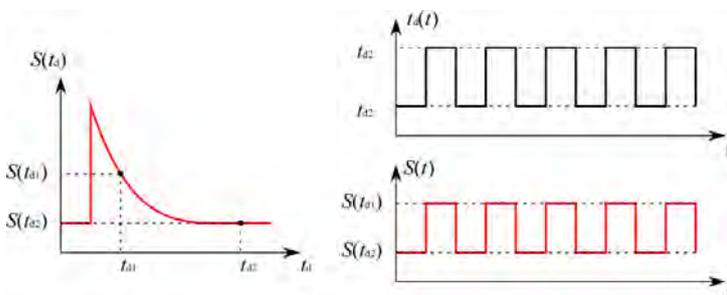
● Delay-time modulation

- Delay time is controlled in a digital form using pulse pickers.



● Lock-in measurement

- Delay time t_d is modulated between t_{d1} (measurement point) and a large value of t_{d2} . The signal $S(t_d)$ is measured by lock-in detection technique.

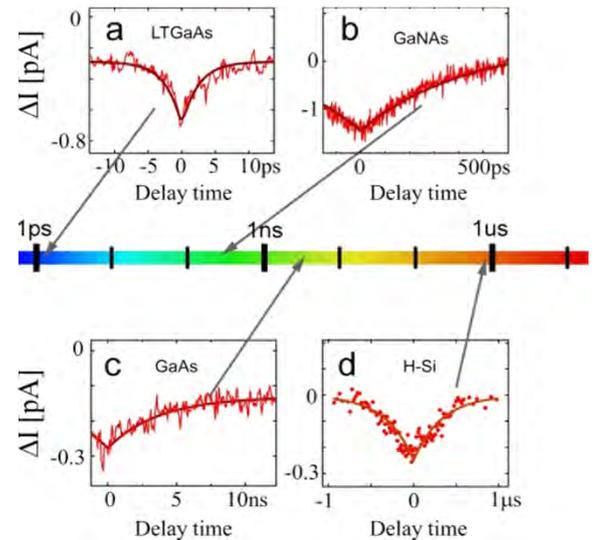


3. Measurement Examples

Real space imaging of transient carrier dynamics in the nanostructures with a wide variety of lifetimes

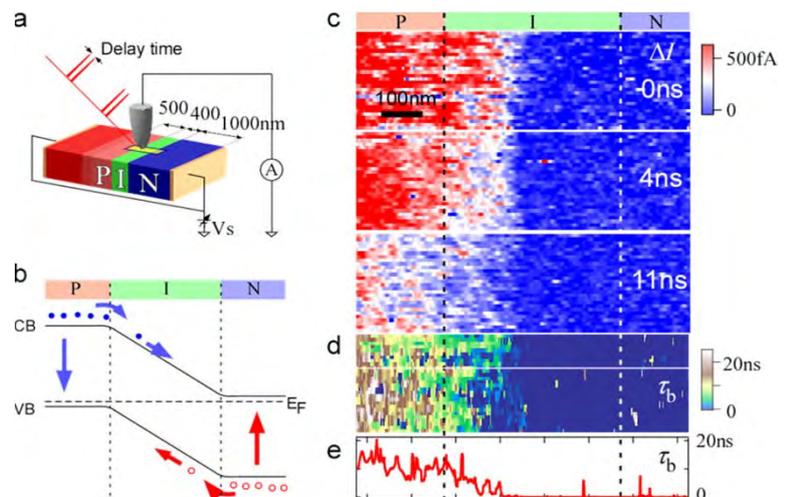
● Carrier lifetimes measured by STM

- Time-dependent STM signals can be obtained for various materials, providing the decay times of photoexcited carriers.



● Imaging nanoscale carrier dynamics

- Observation of diffusion and drift on carrier recombination processes in an inner potential of GaAs PIN structure



4. Patent for licensing

Patent No. : (1) WO/2008/066090, (2) WO/2003/046519 ((1) JP,US,EP,CA,CN,KR (2) JP,US,EP)

Contact : Hisahiro MORIUCHI (JST)
phone : +81-3-5214-8486
e-mail: license@jst.go.jp

Nano-suit: A Thin-layer of Amphiphilic Solution to Observe the Fine Structure of Living Organisms in FE-SEM

Dr. Takahiko HARIYAMA (Hamamatsu University School of Medicine)

1. We can observe living and moving specimens with SEM

- (1) Various complex procedures with fixing tissues have precluded the real fine structure of organisms by a field emission scanning electron microscope.
- (2) **Here we present a new method to observe living organisms**; their surfaces were covered with thin-layers of amphiphilic solution.
- (3) Our method permits the use of a high vacuum ($10^{-4} \sim 10^{-7}$ Pa) and achieves fine structural observations on live specimens.

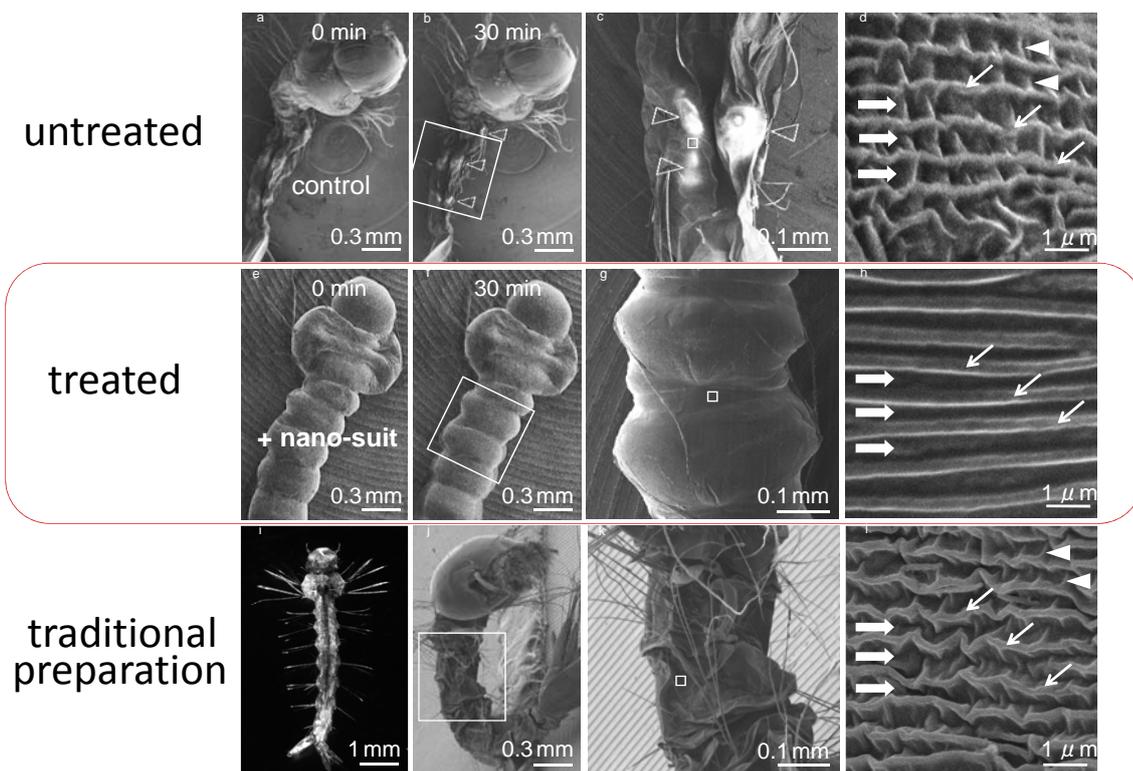
2. Procedure

Animals : Larvae of the northern house mosquito, *Culex pipiens molestus*.

Treatment: Animals were dipped into amphiphilic solution blotted briefly on a dry filter paper to remove excess solution.

SEM observation: Mosquito larvae tolerated the high vacuum well. They continued to actively move around for 30 min under the SEM.

3. Electron micrograph of mosquito larvae



- Untreated larvae quickly shrank and ceased to move under SEM observation (Fig. a-d). There are many wrinkles in the furrows in the two control treatments (Fig. d, i).
- **Treated larvae formed a nano-suit**, showed rapid movements during 30 ± 10 min of SEM observation and suffered no observable morphological change (Fig. e-g). There are no wrinkles in the treated specimen (Fig. h).
- The artificial ECS (extra cellular substances) played a significant role as an extra barrier ameliorating the effects of high vacuum.

4. Patent available for licensing

Patent contact details: Yoshihiro MURAI (JST)
phone: +81-3-5214-8486
e-mail: licence@jst.go.jp

Patent No. : PCT/JP2012/72982
Inventors: Takahiko Hariyama, Masatsugu Shimomura, Yoshinori Muranaka, Hiroshi Suzuki, Yasuharu Takaku, Isao Ohta, Daisuke Ishii, Yuji Hirai

NanoTester : PCI-AFM

(Point-contact Current Imaging Atomic Force Microscopy)

Prof. Takuya MATSUMOTO (Osaka University)

1. NanoTester : PCI-AFM

PROBLEMS

of existing technologies for measuring nanoscale conductance

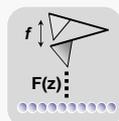
Contact mode?

- Easy operation
- × Degradation of tip and sample



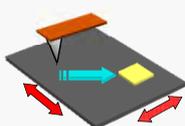
Tapping mode?

- High resolution
- × insufficient electrical contact



Point contact?

- Good electrical contact
- × Mispositioning due to thermal drift

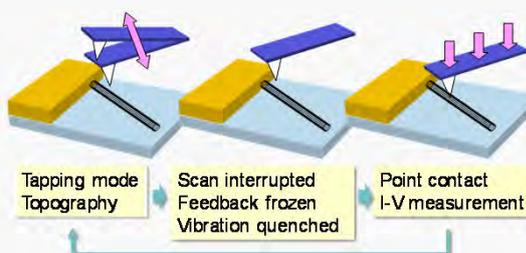


NOVEL TECHNOLOGY "PCI-AFM"

Enables simultaneous nano-scale observation of topography and current image for biomaterials and soft materials

Tapping mode + Point contact
High resolution topography + Stable current-voltage curve measurement

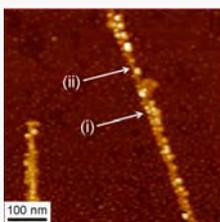
Dynamically switched operation



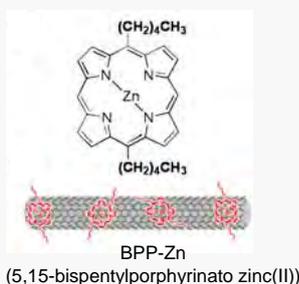
- **Drift free**
: Simultaneous acquisition of topography & Current image
- **High speed measurement**
: 128 X 128 points/10 min
- **High sensitivity** : 100GΩ (10pA)
- **Independent loading force setting**
: Tapping mode (topography) / point contact (current detection)

2. Applications

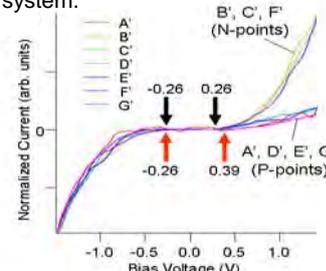
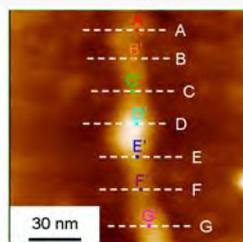
Carbon Nanotube / Porphyrin Complex



CNT / BPP-Zn complex

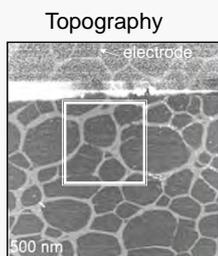


PCI-AFM successfully characterizes the π-Interface between nanotube and molecular system.

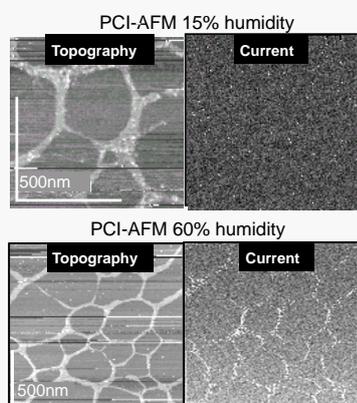


Application No.4

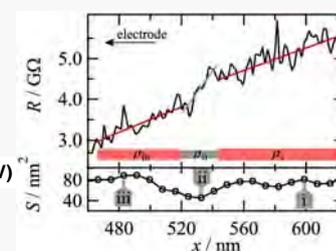
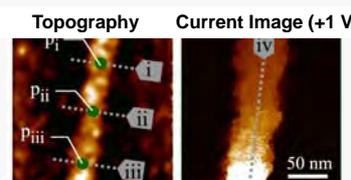
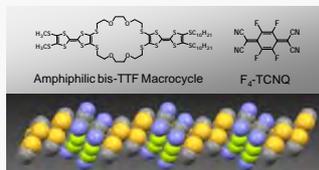
DNA



Application No.5



Charge Transfer Complex



Application No.8

3. Patent available for licensing

Patent No. : US7,088,120, CA2503957 (US, CA)

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PCI-AFM Applications

1. Instrumentation: *Jpn. J. Appl. Phys.* **41**, L742-L744 (2002)
2. Carbon nanotube: *Appl. Phys. Lett.* **82**, 1944-1946 (2003)
3. SAM: *Jpn. J. Appl. Phys.*, **43**, 4511-4516 (2004)
4. Porphyrin/ Carbon nanotube: *Adv. Mater.* **18**, 1411 (2006)
5. DNA network: *Appl. Phys. Lett.* **86**, 113901-113903 (2005)
6. Pb-phthalocyanine nanocrystal: submitted.
7. Tip control methods: *Nanotechnology* **18**, 095501 (2007)
8. Charge transfer complex: *Appl. Phys. Lett.* **93**, 173102 (2008)

Direction-Free Magnetic Field Application System

Dr. Ken HARADA (Hitachi Ltd.)

1. Necessity of direction-free magnetic application system

- Objective : To observe the magnetic structure in materials by TEM using the techniques of
 - 1) Lorentz microscopy
 - 2) electron holography

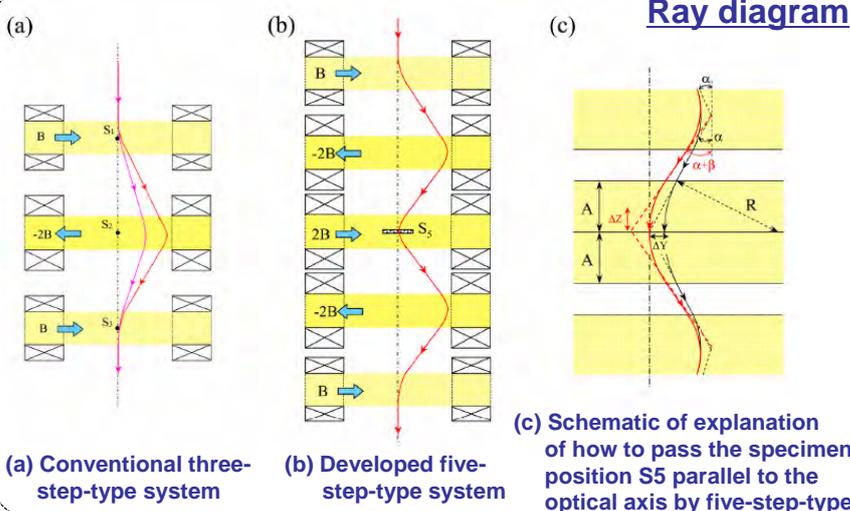
System architecture:

- 1) TEM + 2) **Direction-free magnetic application system (New!)**

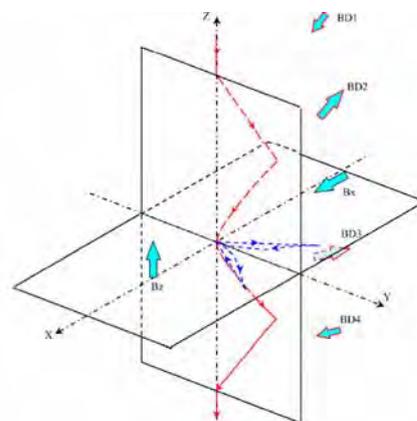
Applying external magnetic field to the specimen

- 1) from an arbitrary direction
- 2) with an arbitrary magnitude
- 3) compensating the electron beam to the optical axis directly

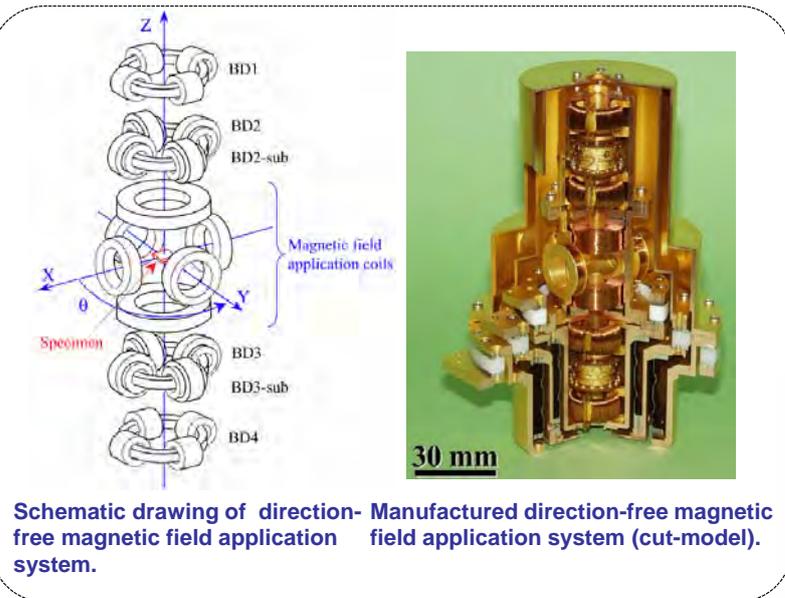
2. Real implementation of the direction-free magnetic field application system



(c) Schematic of explanation of how to pass the specimen position S5 parallel to the optical axis by five-step-type

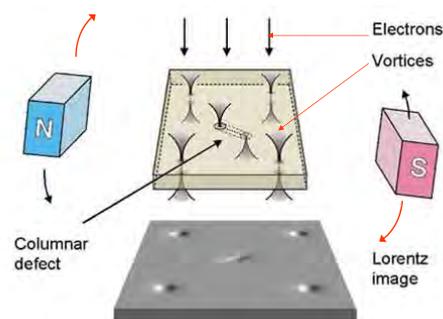


Ray diagram of five-step magnetic field application system within horizontal and vertical magnetic fields applied simultaneously.

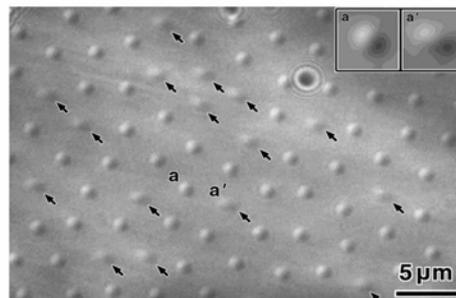


Schematic drawing of direction-free magnetic field application system. Manufactured direction-free magnetic field application system (cut-model).

3. Observed image



Experimental setup of Lorentz microscopy



A Lorentz micrograph of $\text{Bi}_2\text{Sr}_2\text{CaCu}_2\text{O}_{8-\delta}$ (Bi-2212) thin film. Black and white contrast pairs are individual vortices trapped by columnar defects. The image of the perpendicular vortex lines are circular, whereas those of the tilted vortex lines pointed by black arrows are elongated and have lower contrast.

4. Patent available for licensing

Patent No. : US 6838675, EP 1376649

(US, EP(UK, DE, NL))

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About JST

The Japan Science and Technology Agency (JST) is one of the core institutions responsible for the implementation of science and technology policy in Japan, including the government's Science and Technology Basic Plan. From knowledge creation—the wellspring of innovation—to ensuring that the fruits of research are shared with society and Japan's citizens, JST undertakes its mission in a comprehensive manner. JST also works to provide a sound infrastructure of science and technology information and raise awareness and understanding of science and technology-related issues in Japan.

Mission :

We contribute to the creation of innovation in science and technology as the core implementing agency of the fourth phase of the Science and Technology Basic Plan.

Visions :

- 1.To achieve innovation in science and technology through creative research and development.
- 2.To maximize research outcomes by managing research resources on the virtual network.
- 3.To develop the nation's infrastructure for science and technology to accelerate innovation in science and technology.

To Realize Benefits for the Whole of Society from Research Output



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